

Contact mechanics and elements of tribology

Lecture 3. *Surface Roughness*

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@ Centre des Matériaux (& virtually)
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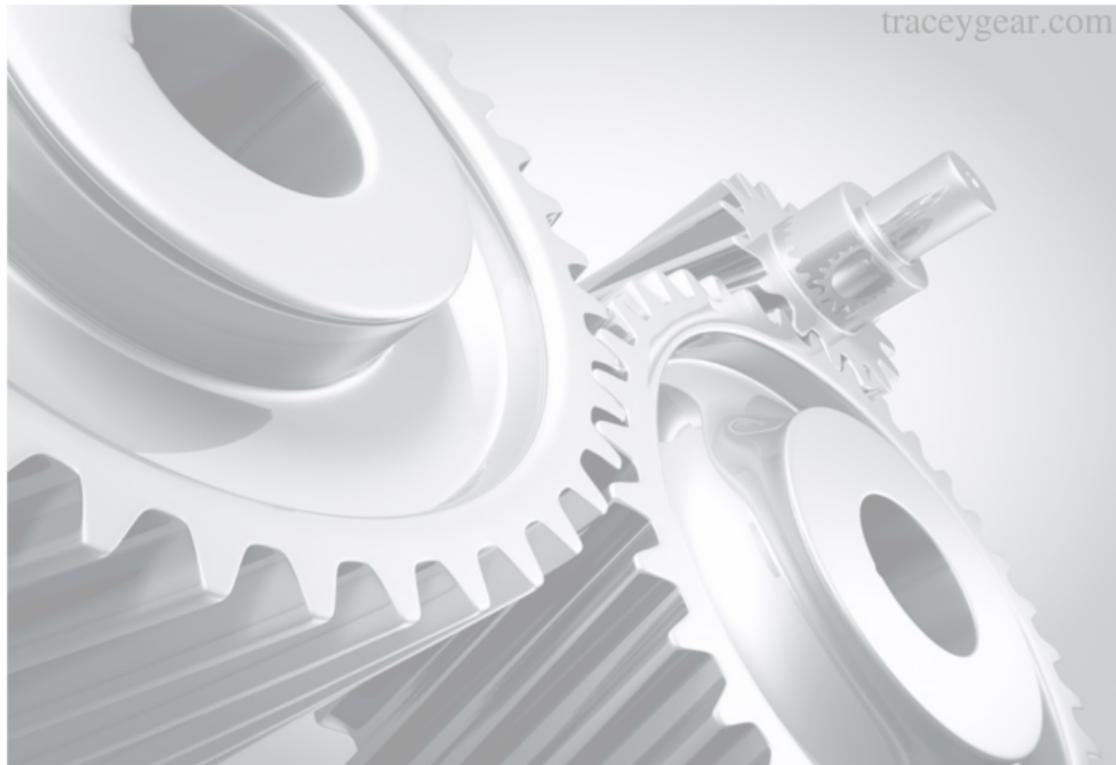


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- Introduction
- Measurement techniques
- Classifications
- Main characteristics
- PDF and PSD
- Random process model of roughness
- Computational roughness models
- Reading

Introduction

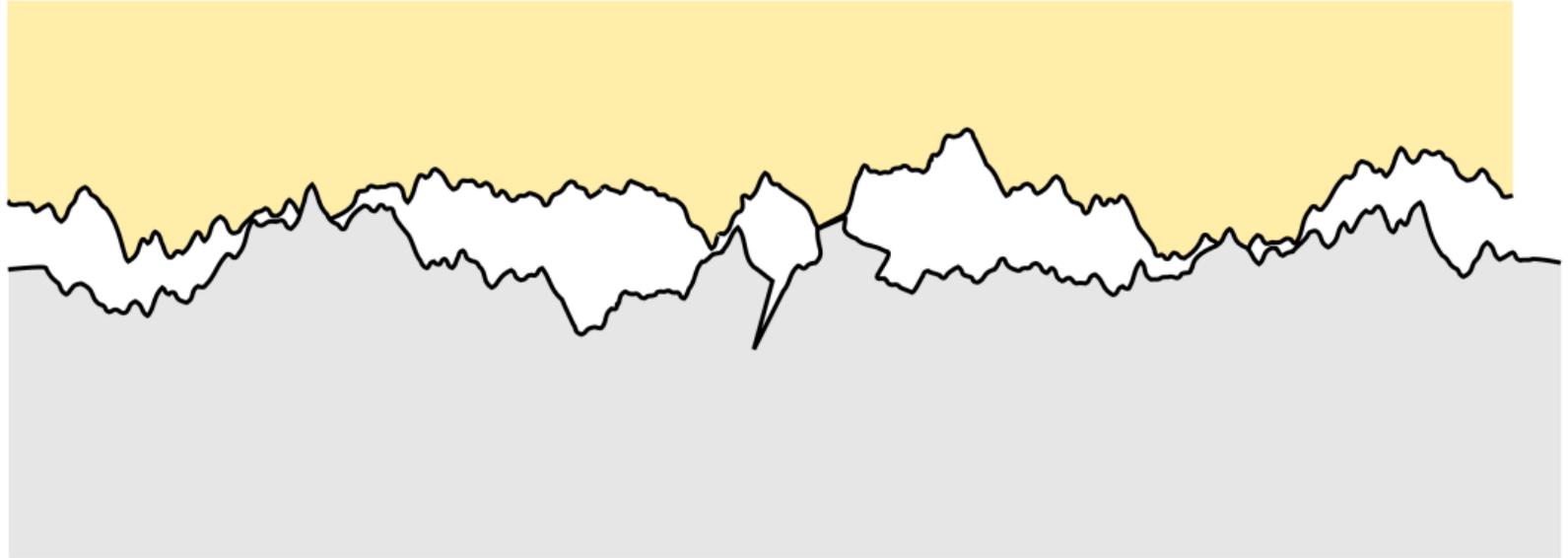
Contact under microscope



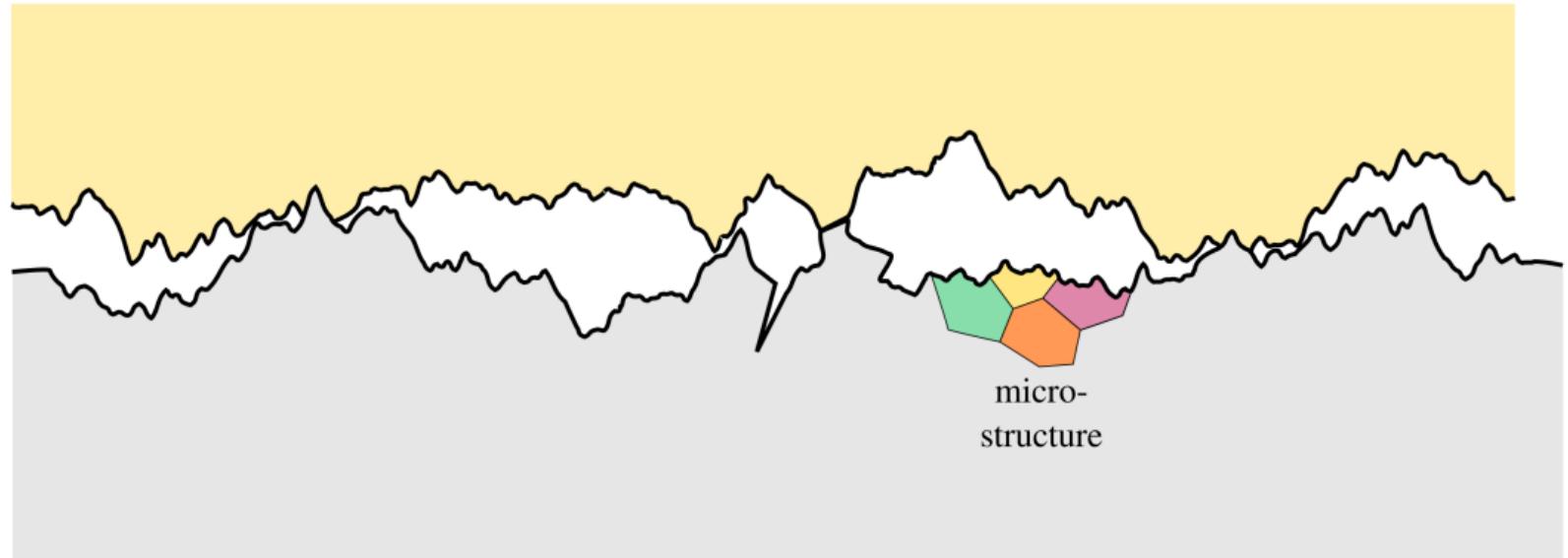
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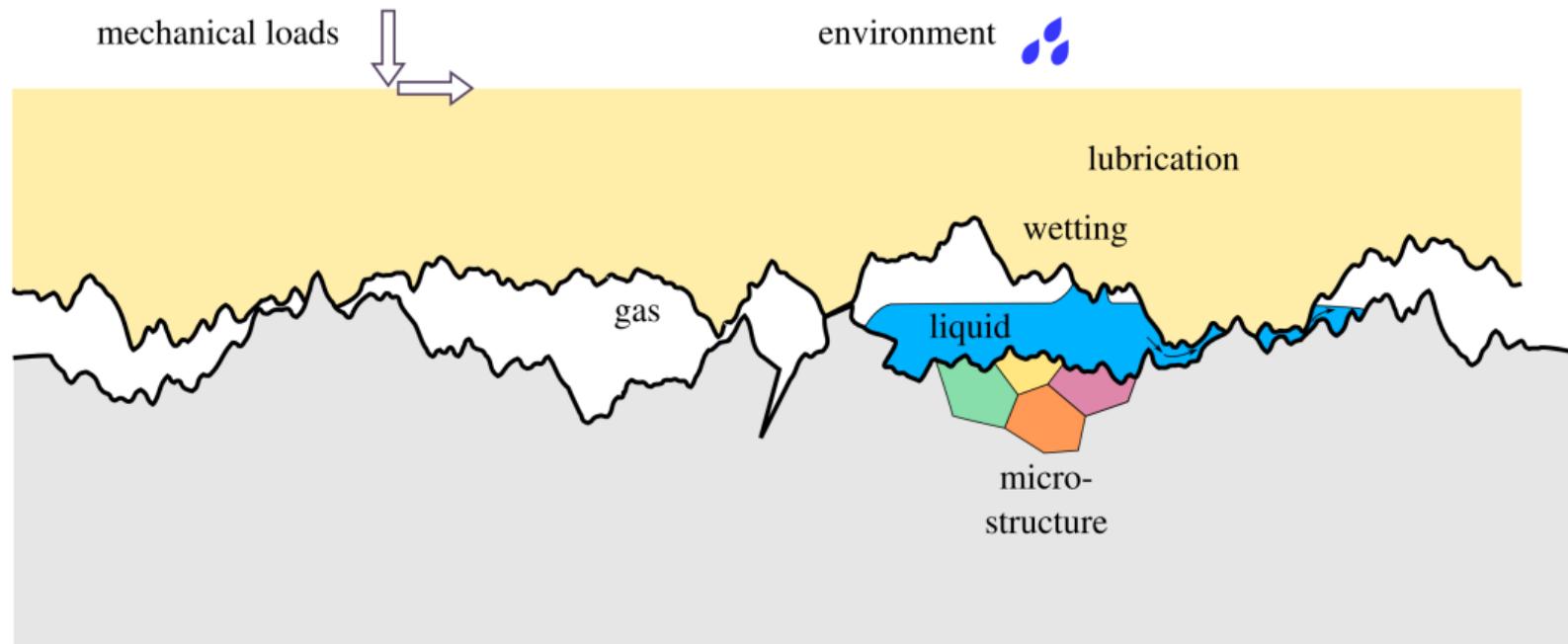
Contact under microscope



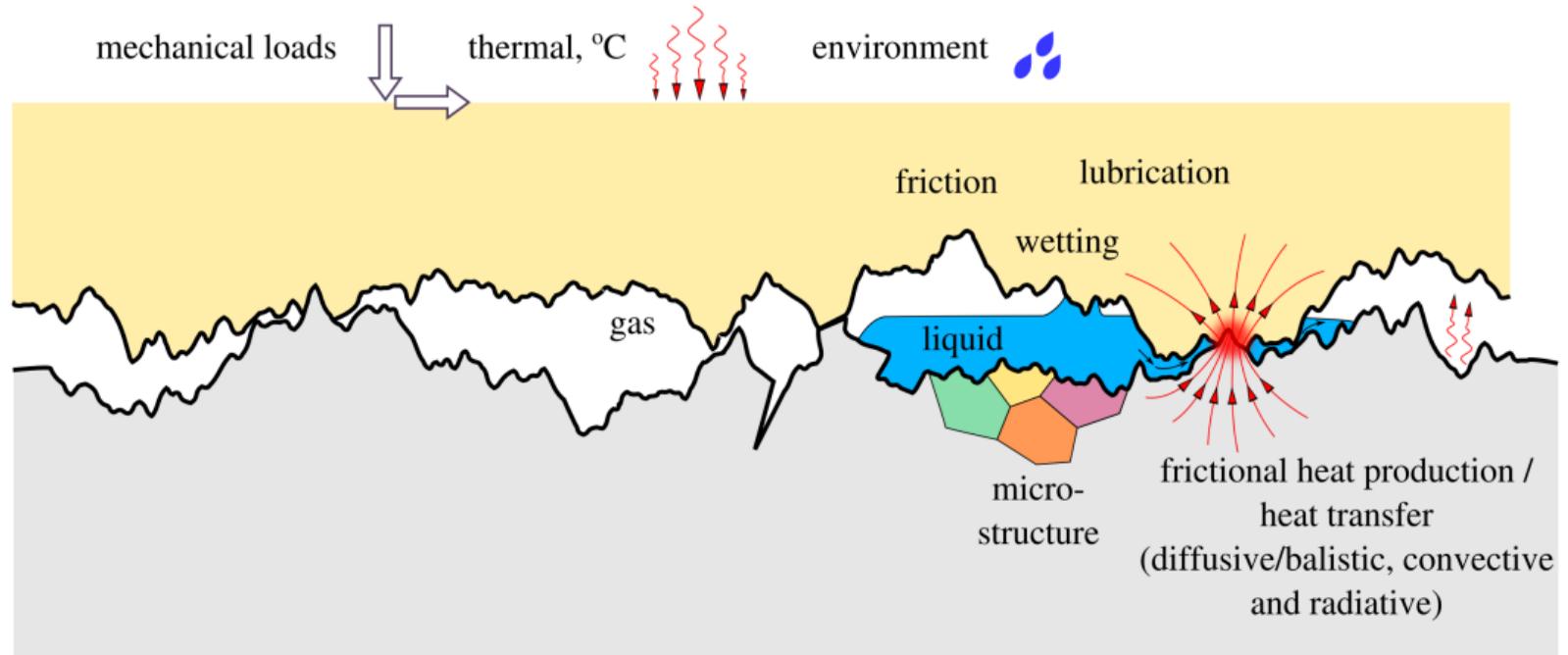
Contact under microscope



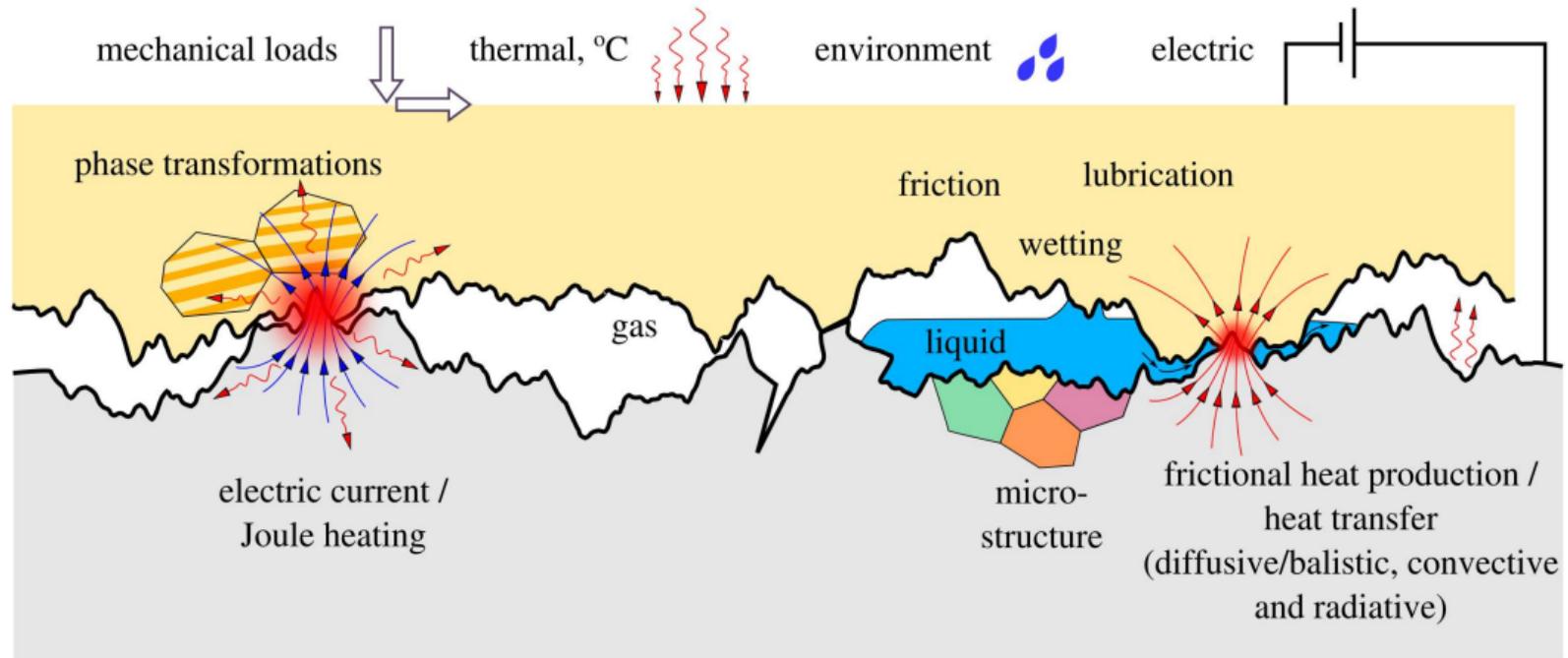
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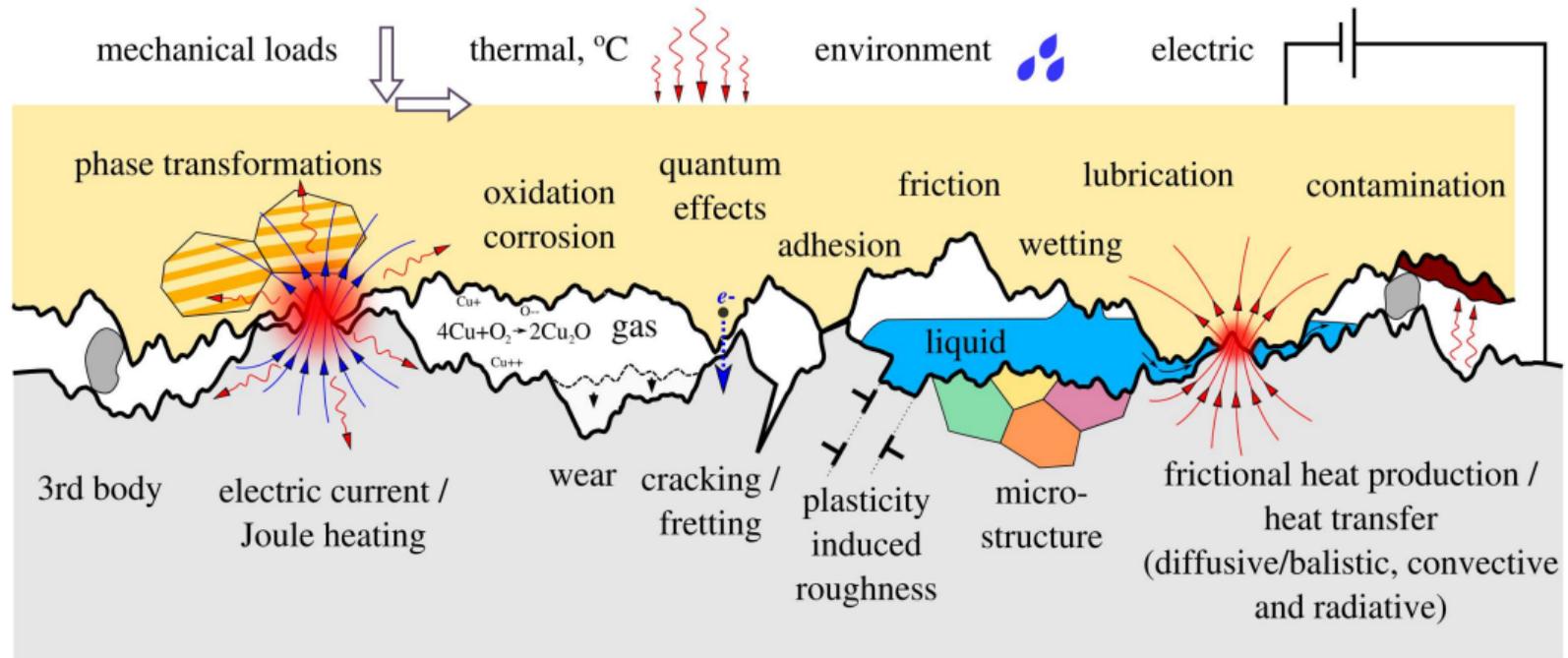
Contact under microscope



Contact under microscope



Contact under microscope



■ Natural and industrial surfaces are *rough*:

- processing
- polishing
- coating
- microstructure
- surface energy
- deformation
- aging
- environment

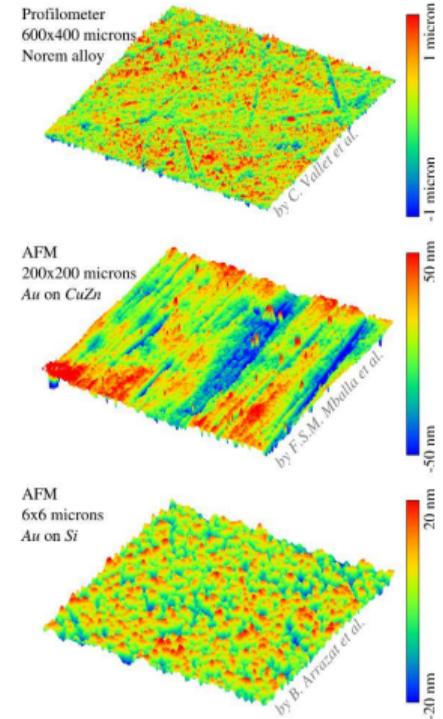


Fig. Examples of rough surfaces

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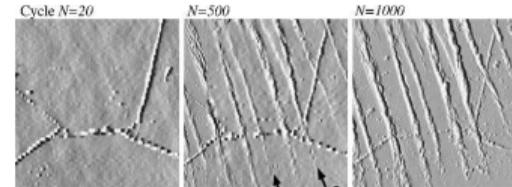


Fig. Persistent slip marks [1]

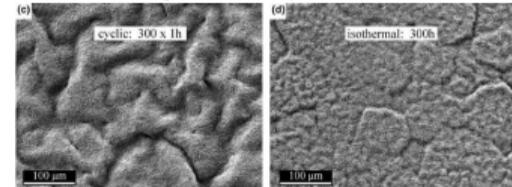


Fig. Rumpling (thermal cycling induced roughness in air)[2]

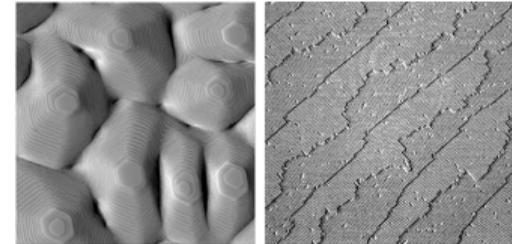


Fig. Epitaxial surface growth [3,4]

[1] J.Polák, J. Man & K. Ortlík, Int J Fatigue 25 (2003)

[2] V.K. Tolpygo, D.R. Clarke, Acta Mat 52 (2004)

[3] M. Einax, W. Dieterich, P. Maass, Rev Mod Phys 85 (2013)

[4] J.R. Arthur, Surf Sci 500 (2002)

■ Natural and industrial surfaces are *rough*:

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■ Roughness affects:

- stress-strain state
- dry friction
- wear
- adhesion
- fluid flow
- sealing
- energy transfer

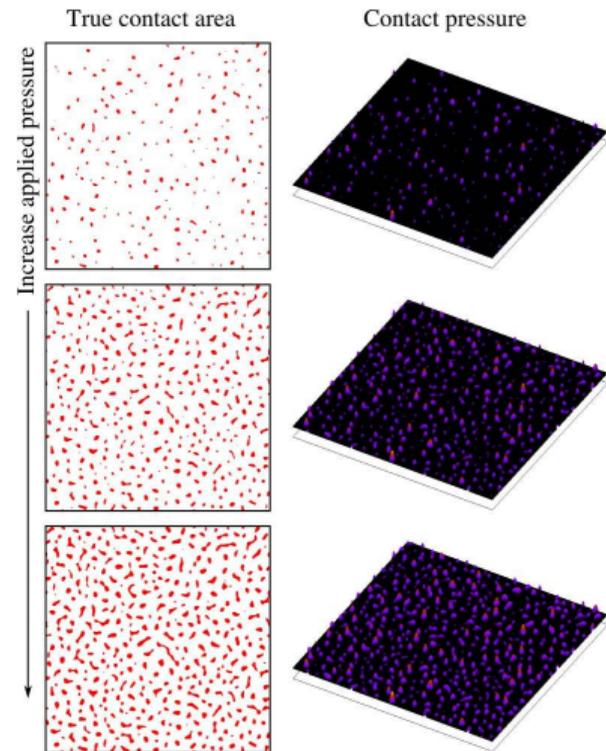


Fig. True contact area and stress fluctuations

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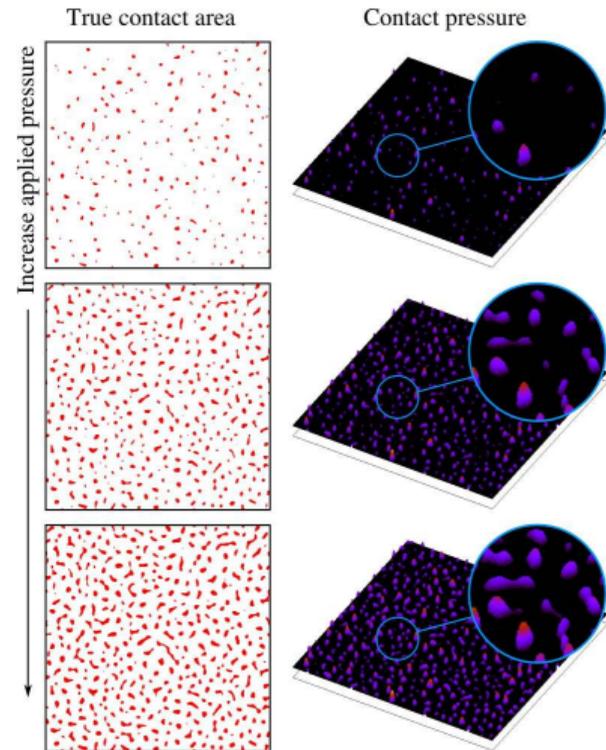


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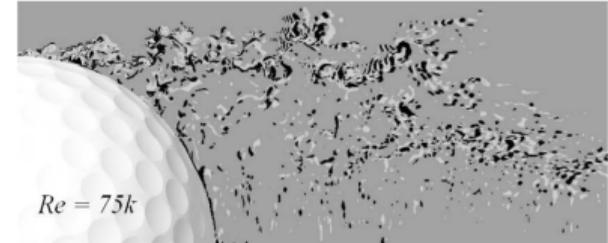
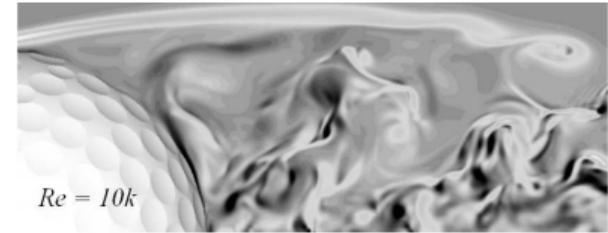


Fig. Numerical simulation of airflow around a (dimpled) golf ball [5]
[5] C.E. Smith, PhD thesis (2011)

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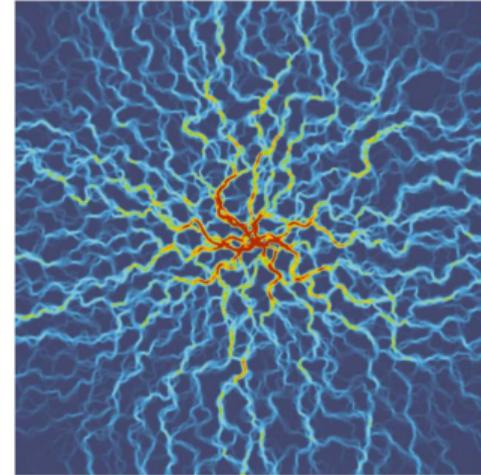


Fig. Fluid passage through free volume between rough surfaces

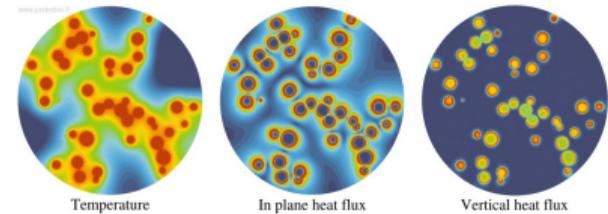


Fig. Heat transfer between rough surfaces
(asperity-based model)

Visible to the naked eye



Granite

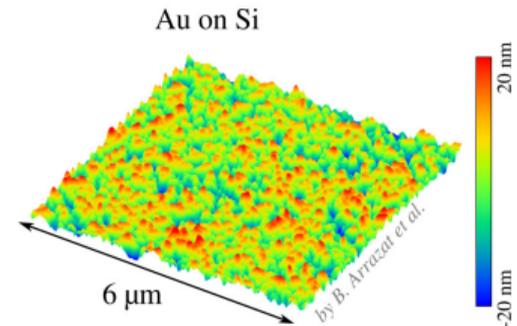
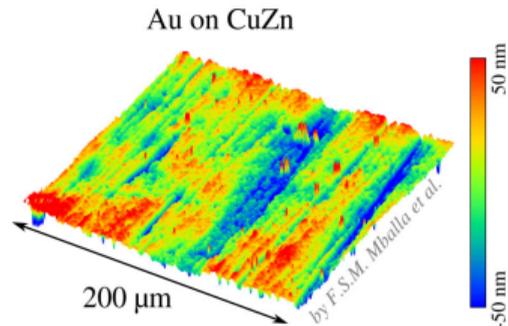
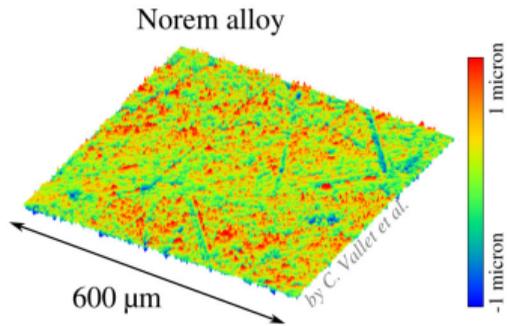


Asphalt concrete



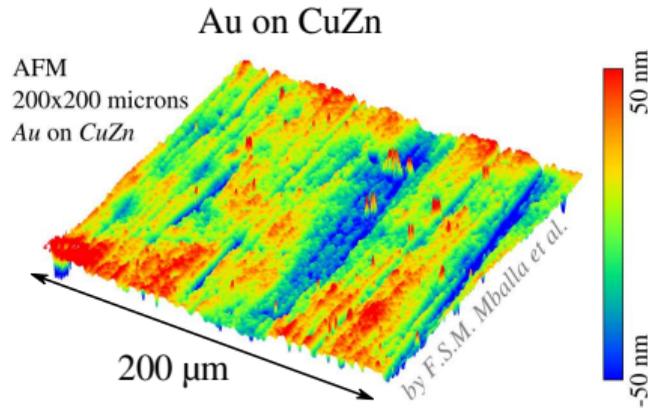
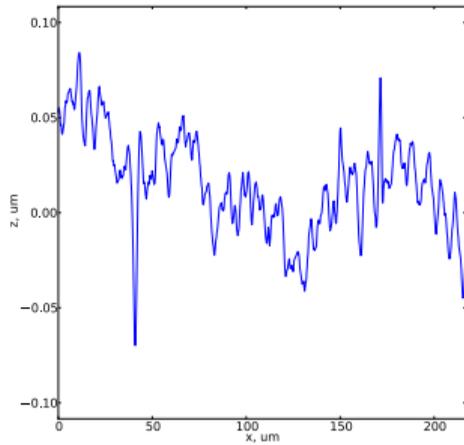
Cracked rock

Seemingly smooth

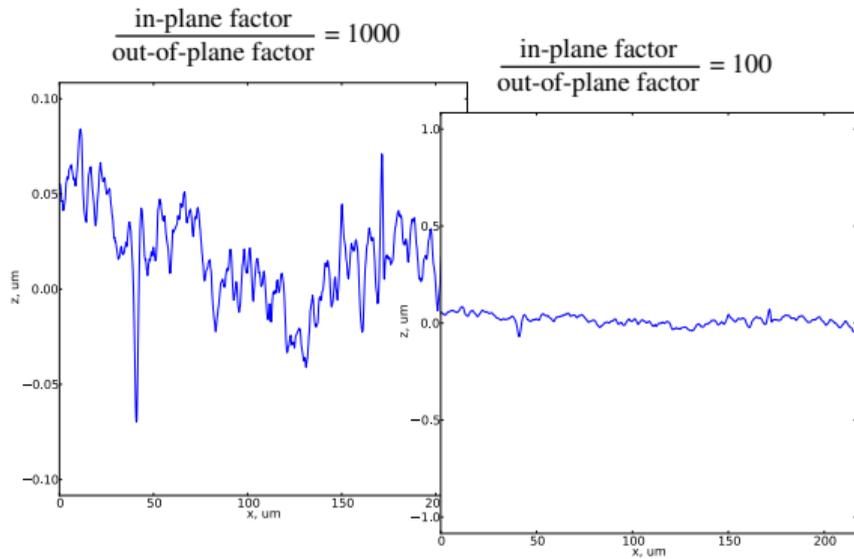


Roughness: in plane and out of plane scales

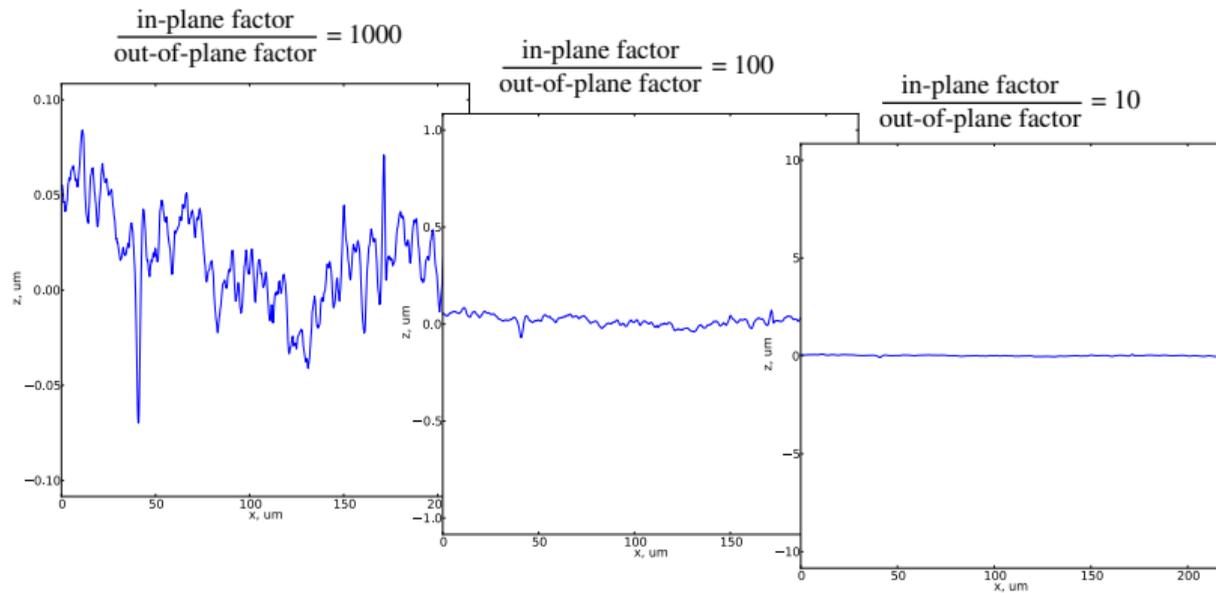
$$\frac{\text{in-plane factor}}{\text{out-of-plane factor}} = 1000$$



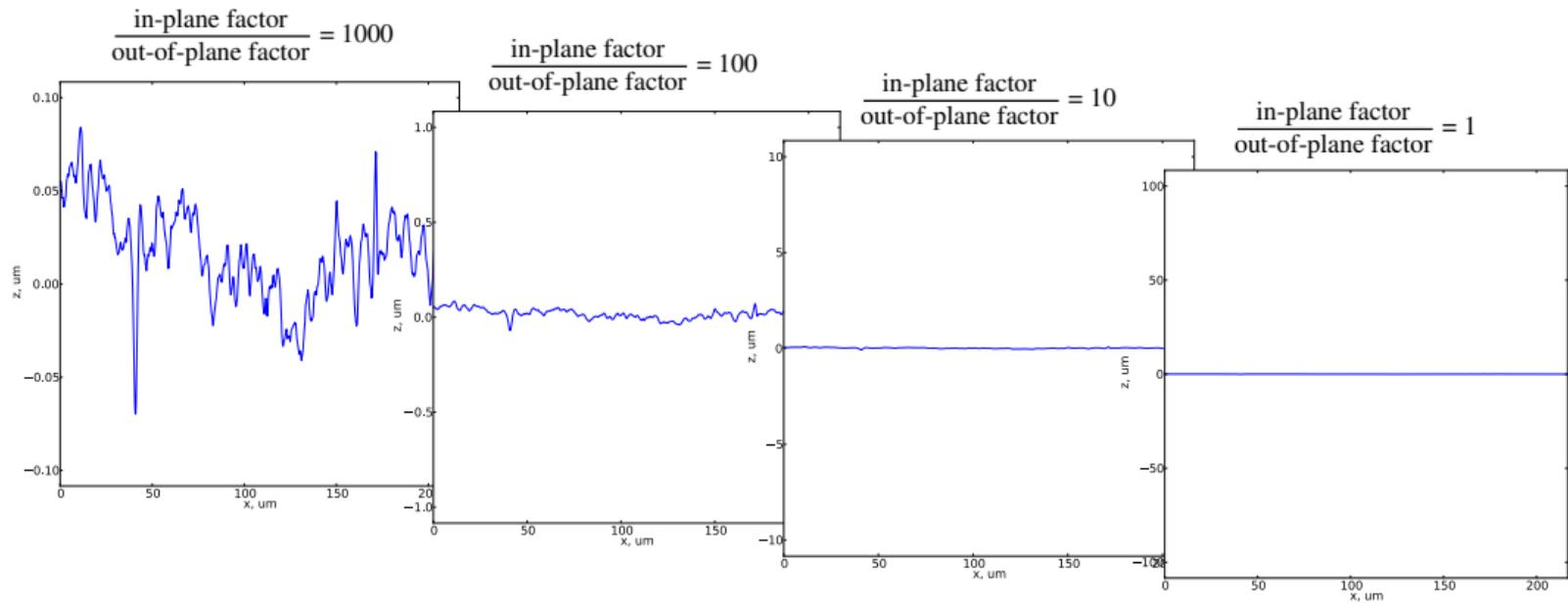
Roughness: in plane and out of plane scales



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Roughness: in plane and out of plane scales



Surface metrology

Surface metrology techniques

■ Stylus measurements

- Mechanical contact of a tip with surface
- Force $\geq 3\mu\text{g}$, tip radius $\geq 50\text{ nm}$
- Mainly for profile measurements $y(x)$

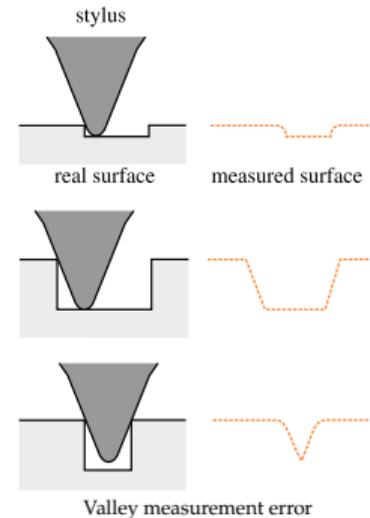
■ Optical measurements

- Confocal (laser scanning) microscopy
 - highest lateral resolution
- Interferometry (WLI):
 - highest vertical resolution
 - 10 to 100 times faster than CM
- Scanning Electronic Microscopy (SEM):
 - in secondary electron emission
 - electrons penetrate in the matter \rightarrow roughness smoothing
 - conducting materials

■ Nano-contact measurements

- Atomic Force Microscopy (AFM)
 - roughness + adhesive and elastic properties
- Scanning Tunneling Microscope (STM)

Stylus profilometer



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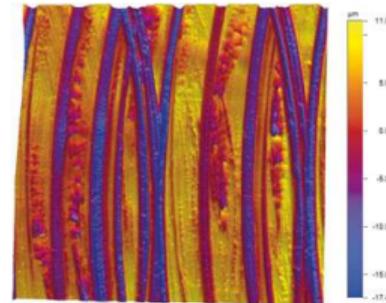
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Stylus profilometer



Modern stylus profilometer
www.bruker.com



Roughness measurements ($\Delta z \approx 30\ \mu\text{m}$)
www.icryst.com

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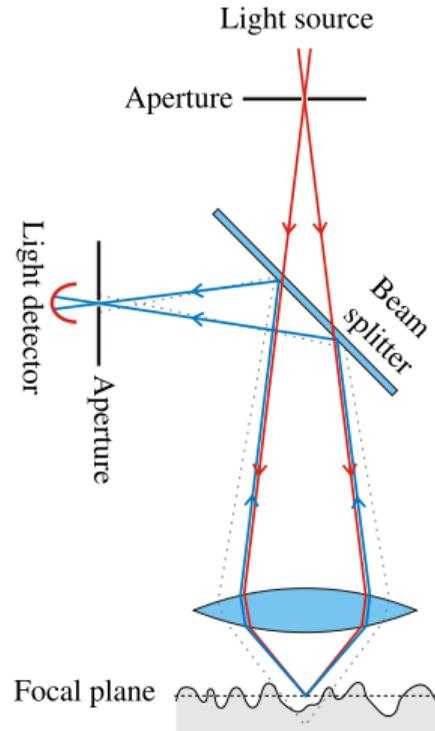
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Confocal microscopy



Principle of confocal microscopy
adapted from www.wikipedia.org

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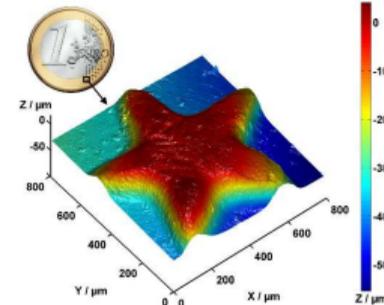
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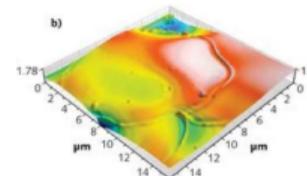
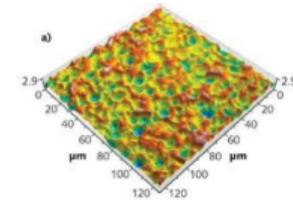
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Confocal microscopy



1 euro surface www.wikipedia.org



Stainless steel machined with micro-electric discharge

www.laserfocusworld.org

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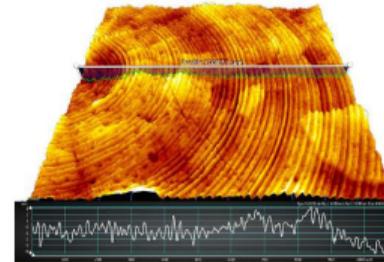
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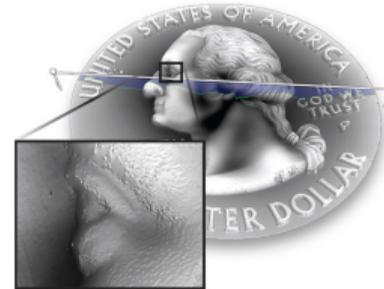
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White Light Interferometry



Diamond-turned optics www.zygo.com



US quarter surface www.zygo.com

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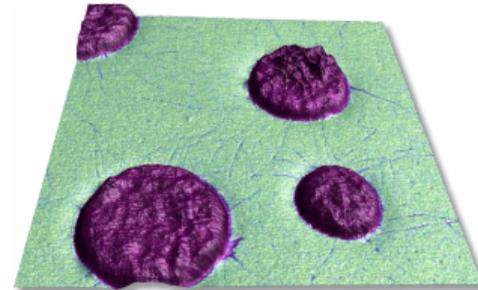
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AFM



Modern AFM
www.bruker.com



Roughness and elastic moduli (color) of polymer blend
www.bruker.com

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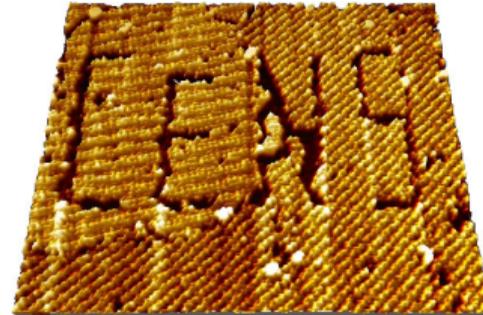
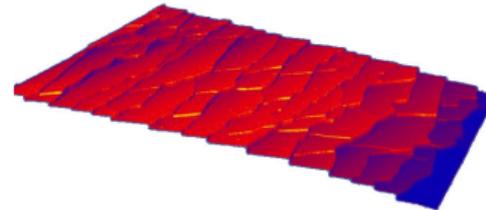


Fig. Center for NanoScience logo imprinted at atomic scale

www.cens.de



Atomic steps on platinum surface
(500x500 nm)

www.icryst.com

Roughness Characterization

Roughness: classification

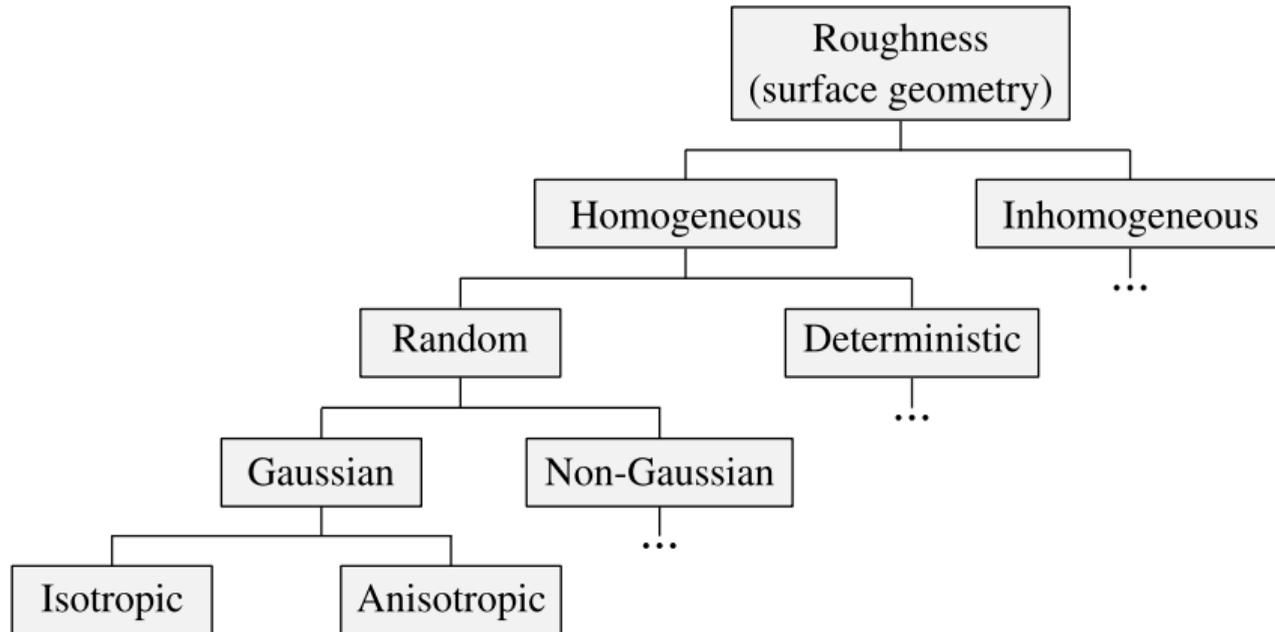


Fig. Roughness classification according to Nayak^[1]

[1] Nayak, J. Lub. Tech. (ASME) 93:398 (1971)

Roughness: classification

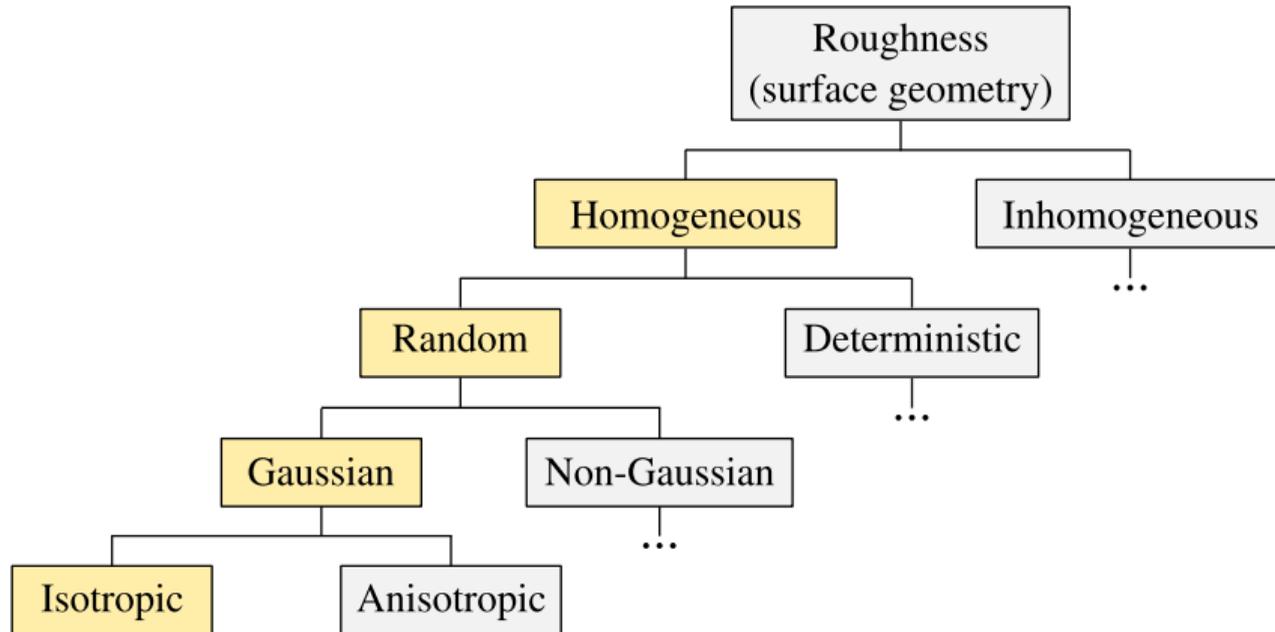


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Roughness and geometry/form

- How to separate roughness from surface geometry?
- Most metrology software enable *simple* shape removal

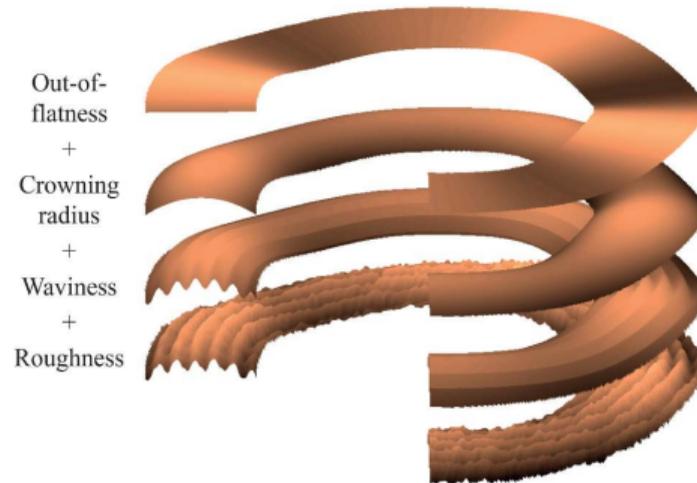


Fig. Circular metallic seal with turned copper surface^[1]

[1] F.P. Rafòls, Licentiate Thesis, LTU 2016.

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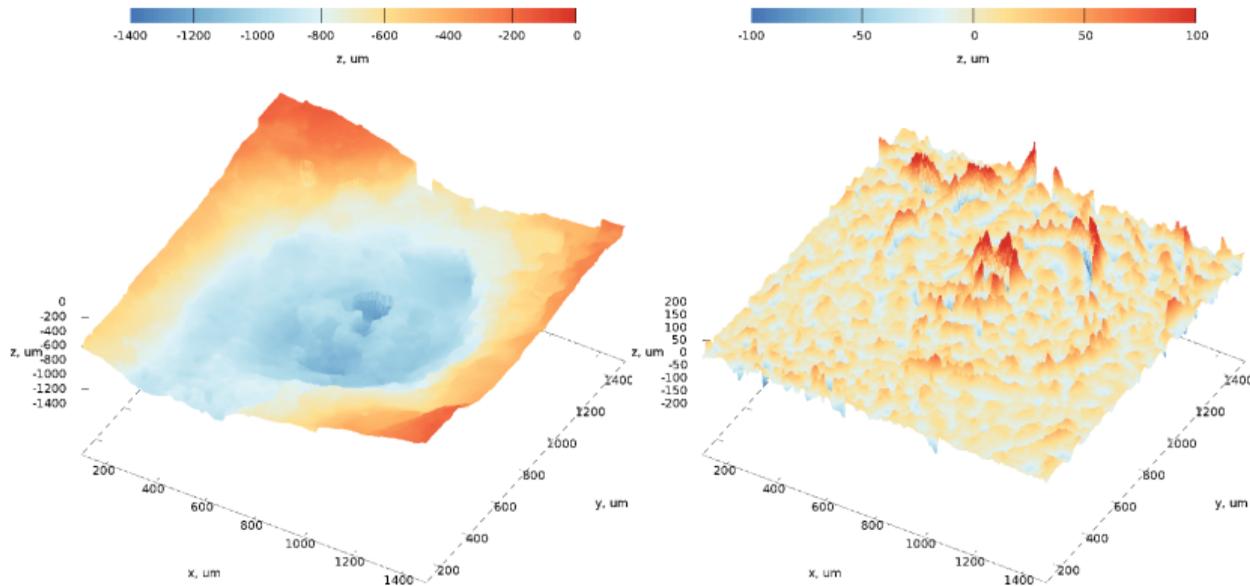


Fig. (left) impact crater, (right) shape is filtered out

Roughness and geometry/form

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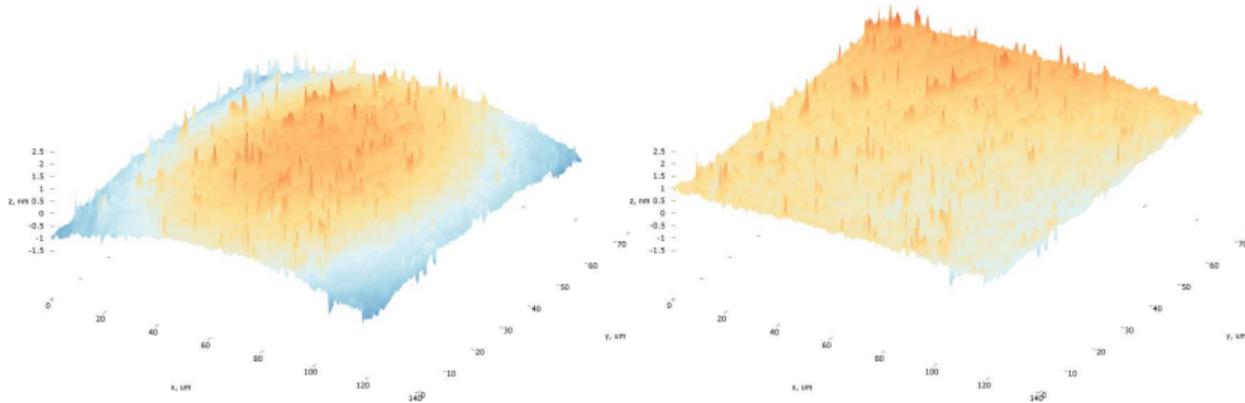
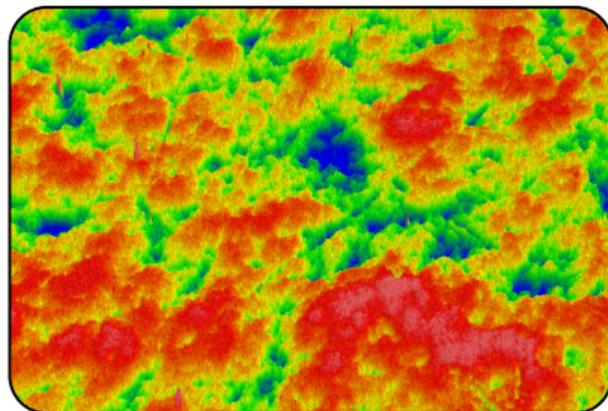


Fig. (left) spherical indenter, (right) $z = a(x^2 + y^2)$ shape is subtracted

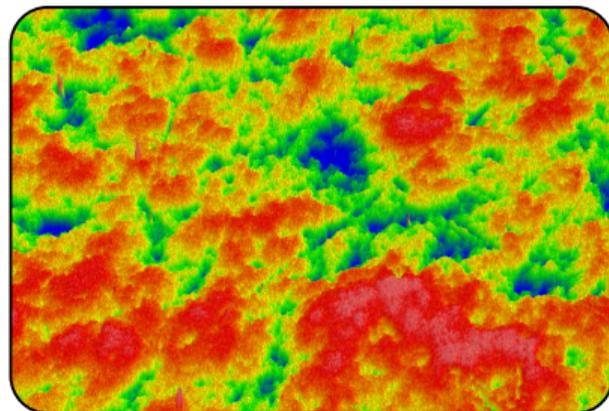
Surface characterization

- Let $z(x, y) : \mathbb{R}^2 \mapsto \mathbb{R}$ is a single-valued function
- For the average operator $\langle \bullet \rangle = \frac{1}{A} \int_A \bullet dA$
- Centered $\langle z \rangle = 0$
- No tilt $\langle \nabla z \rangle = 0$
- No curvature $\langle \nabla \nabla z \rangle = 0$



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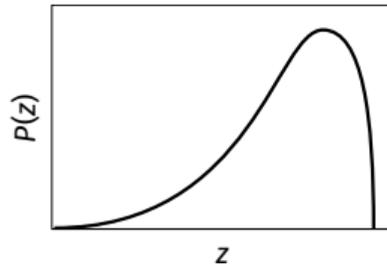
- 1 Height probability density (PDF) of z :

$$P(z)$$

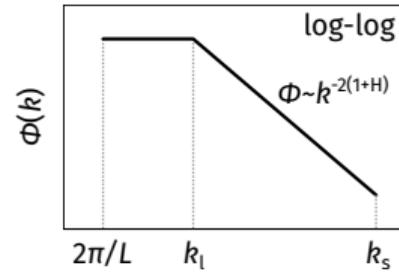
- 2 Fourier Transform of z :

$$\text{FT}(z(x, y)) = \hat{z}(k_x, k_y)$$

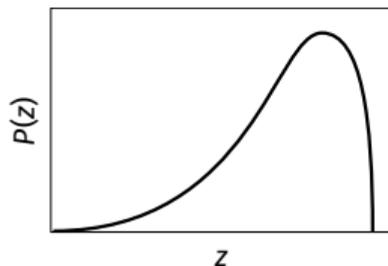
PDF
probability density



PSD
spectral density



PDF probability density



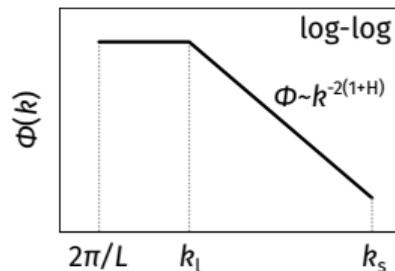
- Function

$$P(z) = \langle \delta(z - z'(x, y)) \rangle$$

- Probability moments

$$s_p = \int_{z \in \mathbb{R}} z^p P(z) dz$$

PSD spectral density



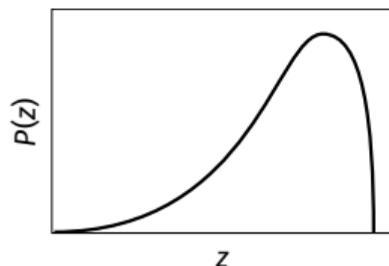
- Function

$$\Phi(k_x, k_y) = \frac{1}{4\pi^2 A} |\text{FT}(z(x, y))|^2$$

- Spectral moments

$$m_{pq} = \int_{k_x, k_y \in \mathbb{R}} k_x^p k_y^q \Phi(k_x, k_y) dk_x dk_y$$

PDF
probability density



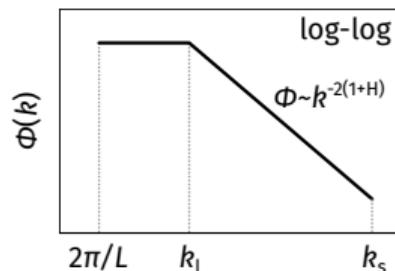
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PSD
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Link between the PDF and the PSD: $\langle z^2 \rangle = s_2 = m_{00}$

Often rough surfaces are

- Gaussian

$$P_{\text{ens.}}(z) = \mathcal{N}(0, \sigma^2)$$

- Isotropic (rotational invariance of the spectrum)

$$\Phi_{\text{ens.}}(k_x, k_y) = \Phi_{\text{ens.}}(|\underline{\mathbf{k}}|)$$

- Self-affine

$$\Phi_{\text{ens.}}(|\underline{\mathbf{k}}|) \sim |\underline{\mathbf{k}}|^{-2(1+H)}, \quad H \in (0, 1)$$

- Ergodic

$$P_A(z) = \langle \delta(z - z'(x, y)) \rangle_A \xrightarrow{A \rightarrow \infty} P_{\text{ens.}}(z)$$

Parametrize roughness

Sampling-step independent characteristics:

- Root mean squared roughness*

$$S_q = \sqrt{\langle z^2 \rangle} = \sqrt{s_2} = \sqrt{m_0}$$

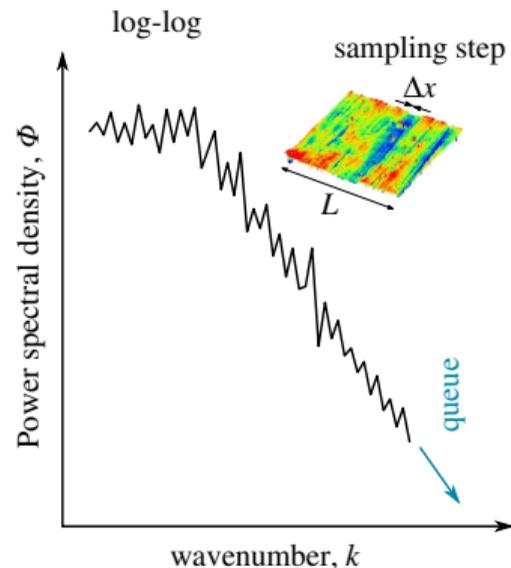
- Hurst exponent $0 < H < 1$ of the PSD decay

$$\Phi \sim k^{-2(1+H)}$$

***Warning!** S_q can be scale-dependent^[1,2], i.e. $S_q = S_q(L)$

[1] R.S. Sayles and T.R. Thomas, *Nature* 271:431-434 (1978).

[2] A. Pradha, M.H. Müser, L. Pastewka, T. Jacobs *and many others*. "The Surface Topography Challenge...", *Tribology Letters* (2025)



Parametrize roughness

Sampling-step independent characteristics:

- Root mean squared roughness*

$$S_q = \sqrt{\langle z^2 \rangle} = \sqrt{s_2} = \sqrt{m_0}$$

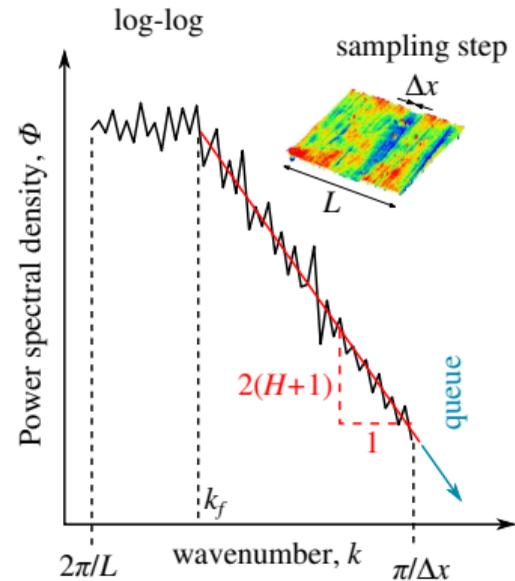
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Parametrize roughness

Sampling-step dependent characteristics:^[3]

- Root mean squared gradient

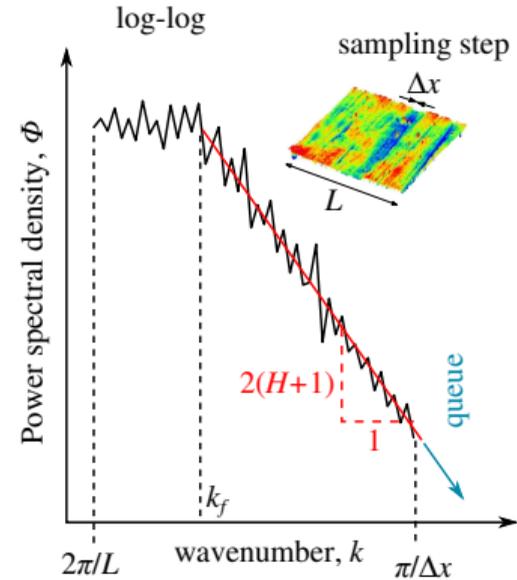
$$S_{dq} = \sqrt{\langle |\nabla z|^2 \rangle} = \sqrt{2m_2}$$

- Root mean squared curvature

$$S_{ddq} = \sqrt{\langle \|\nabla \nabla z\|_F^2 \rangle} = \sqrt{m_4}$$

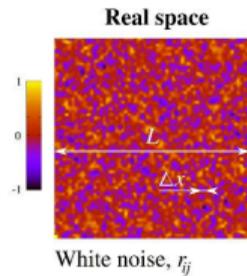
- Nayak parameter

$$\alpha = \frac{m_0 m_4}{m_2^2}$$



[3] P.R. Nayak, Random Process Model of Rough Surfaces, ASME J Lubric Techn, 1971

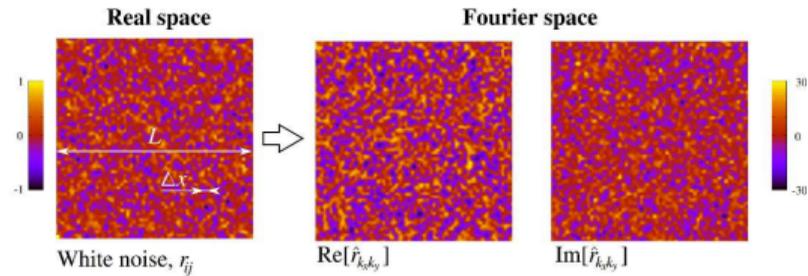
Roughness modelling



Fourier space

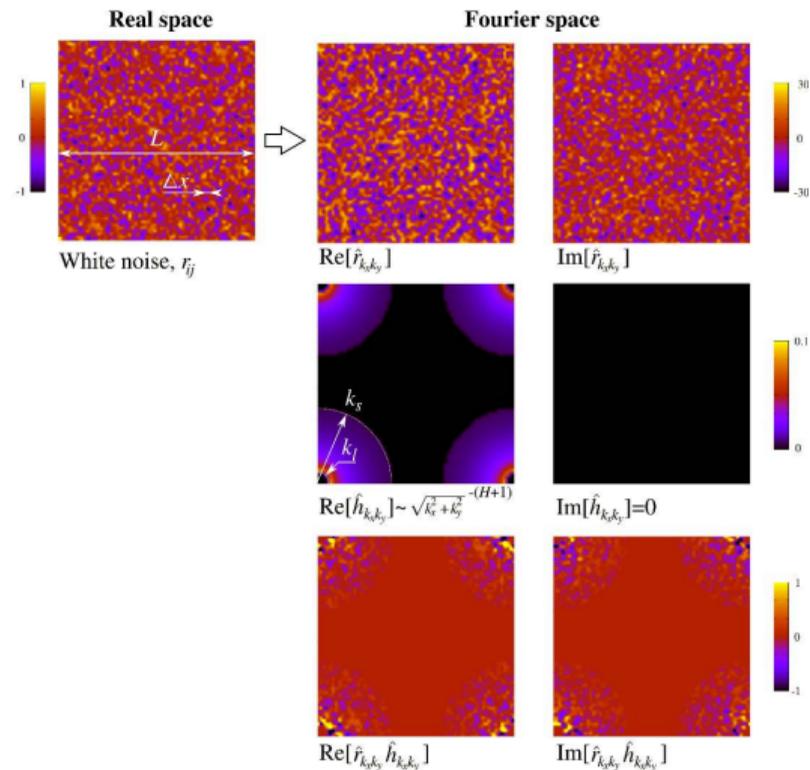
- [1] Y. Z. Hu and K. Tonder, Int. J. Machine Tools Manuf. 32, 83 (1992)
[2] Roughness generator <https://github.com/vyastreb/rfgen>

Roughness modelling



- [1] Y. Z. Hu and K. Tonder, Int. J. Machine Tools Manuf. 32, 83 (1992)
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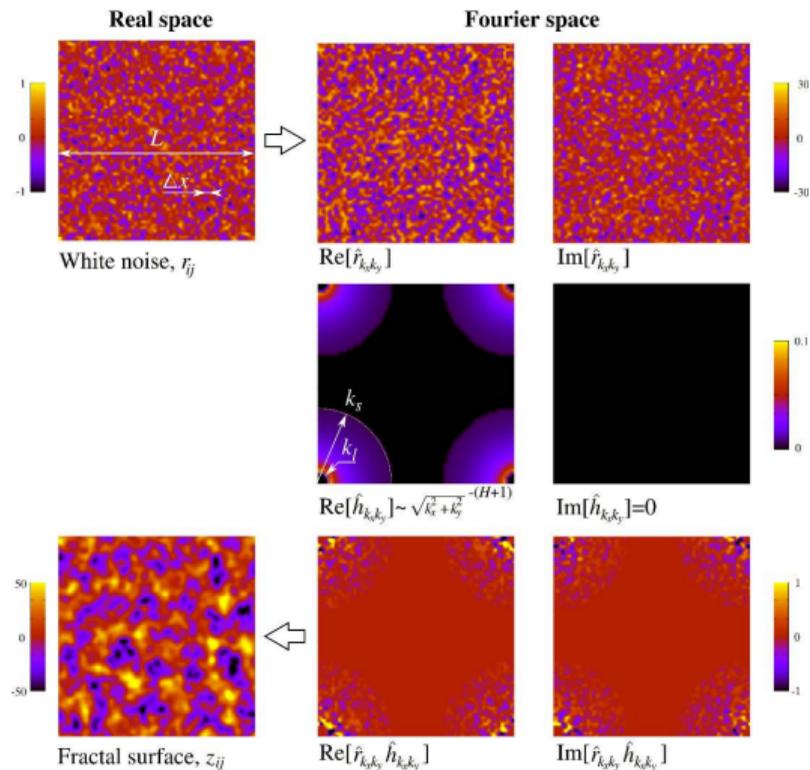
Roughness modelling



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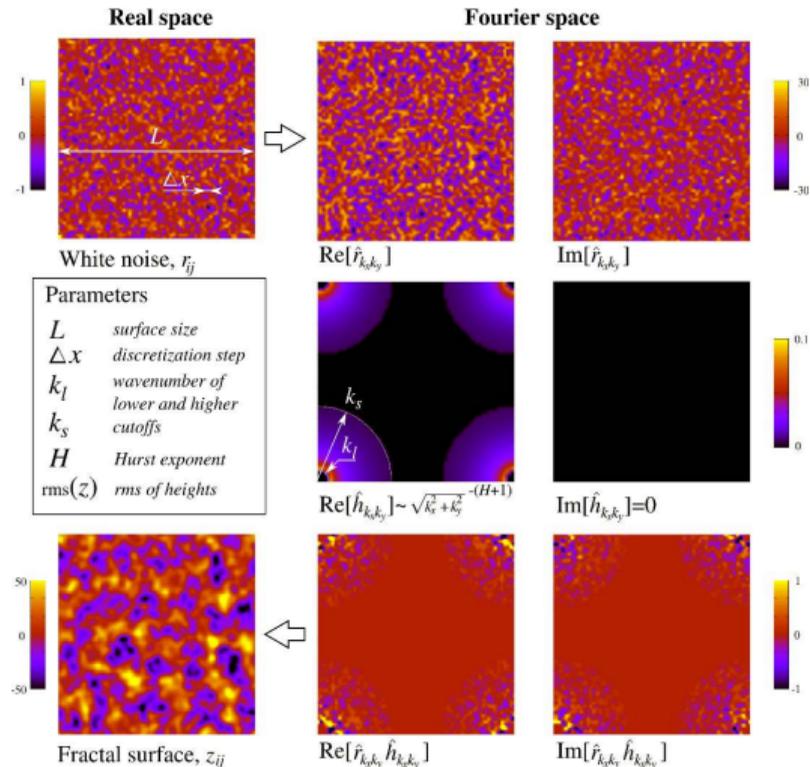
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Roughness modelling

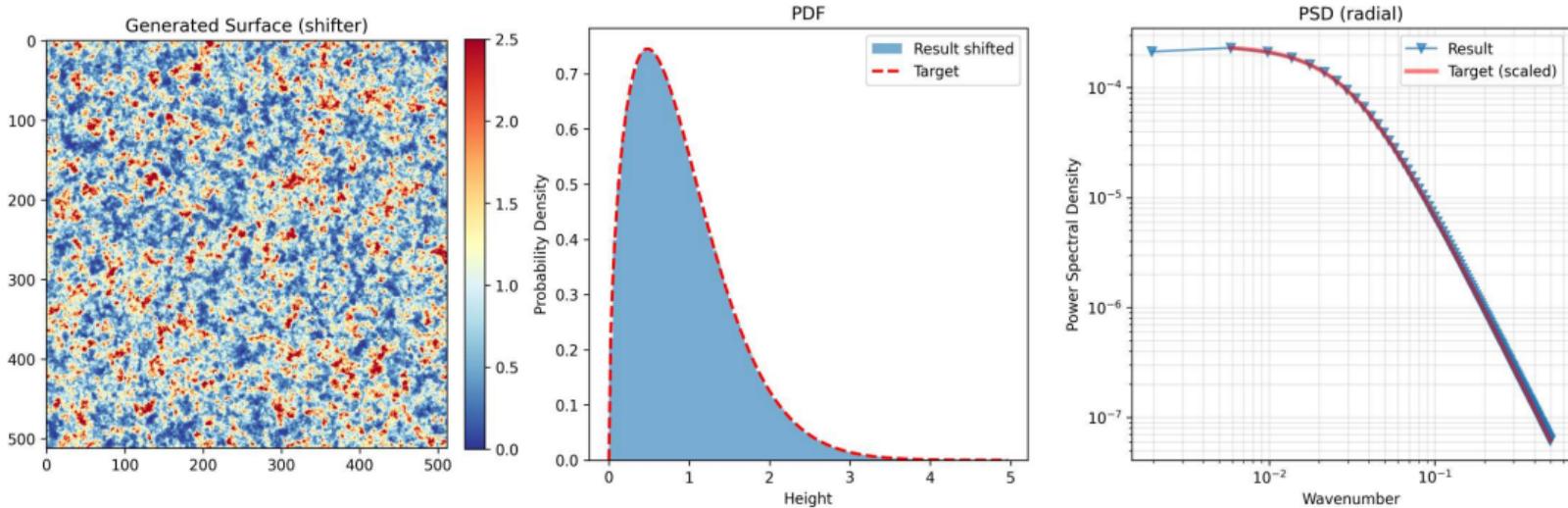


[1] Y. Z. Hu and K. Tonder, Int. J. Machine Tools Manuf. 32, 83 (1992)

[2] Roughness generator <https://github.com/vyastreb/rfgen>

Non-Gaussian roughness modelling

- Example: Weibull PDF and Matérn PSD

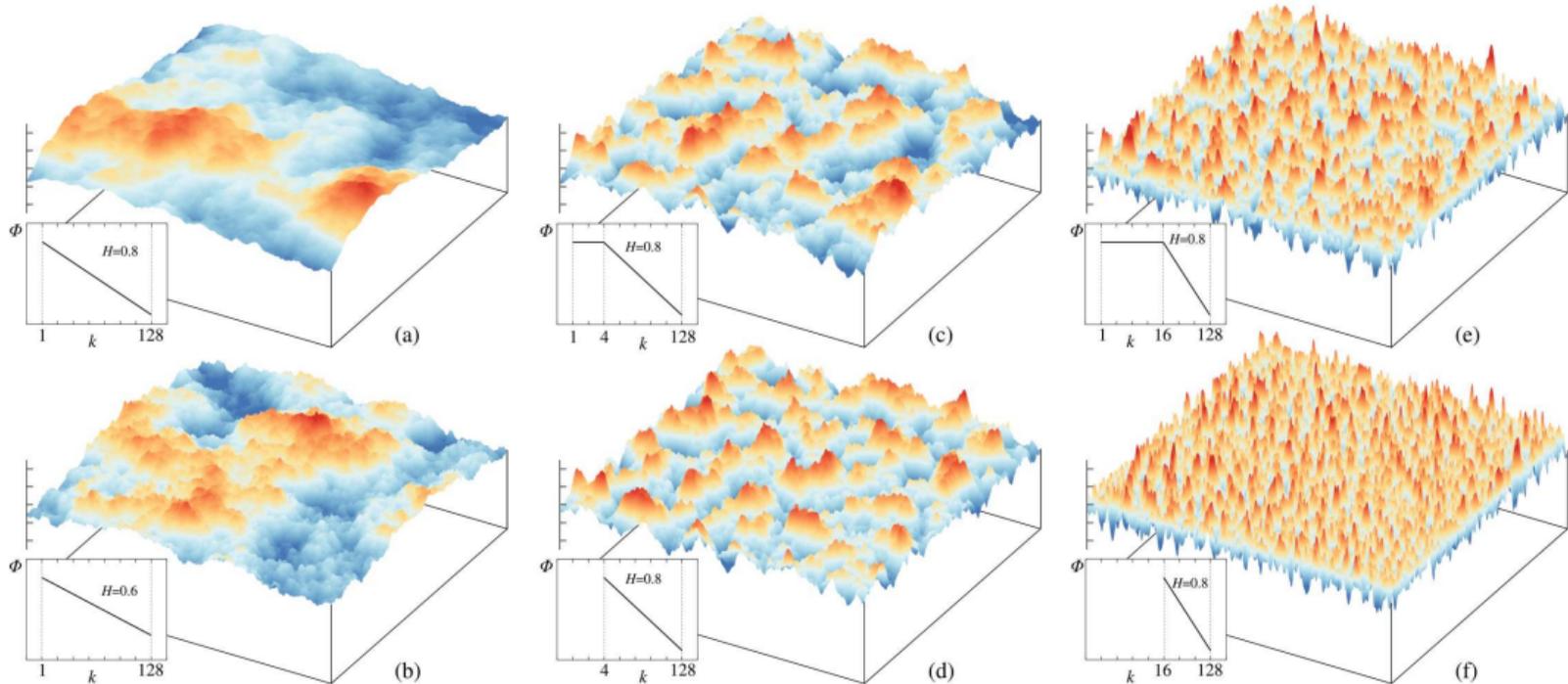


[1] Schreiber, T. and Schmitz, A. (1996). Improved surrogate data for nonlinearity tests. *Phys. Rev. Lett.* 77.

[2] Pérez-Ràfols, F. and Almqvist, A. (2019). Generating randomly rough surfaces with given height probability distribution and power spectrum. *Tribol. Int.* 131

[3] Roughness generator <https://github.com/vyastreb/rfgen>

Model roughness: isotropic, Gaussian, self-affine



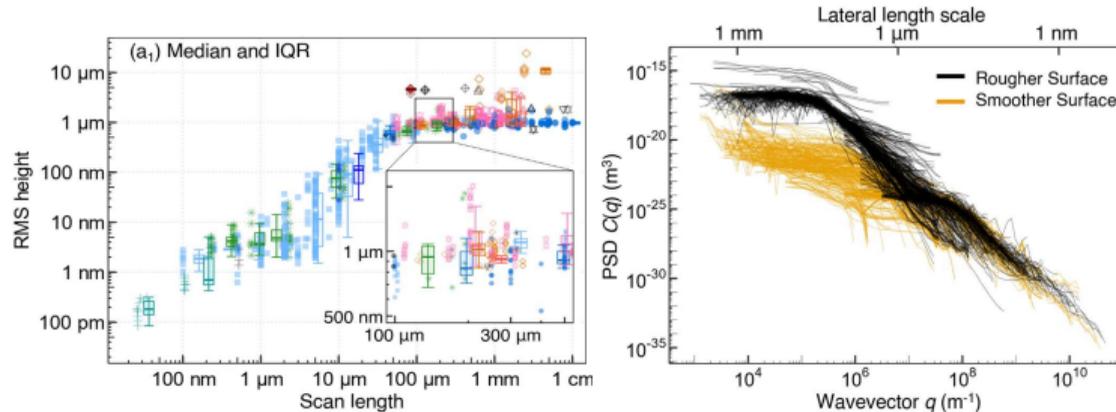
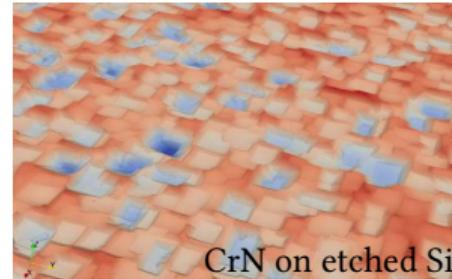
[2] V.Y., G. Anciaux, J.F. Molinari, *Tribol. Int.* 114:161-171 (2017)

The Surface-Topography Challenge

A. Pradhan, M.H. Müser, L. Pastewka, T. Jacobs *et al.*, Tribology Letters 73, 2025

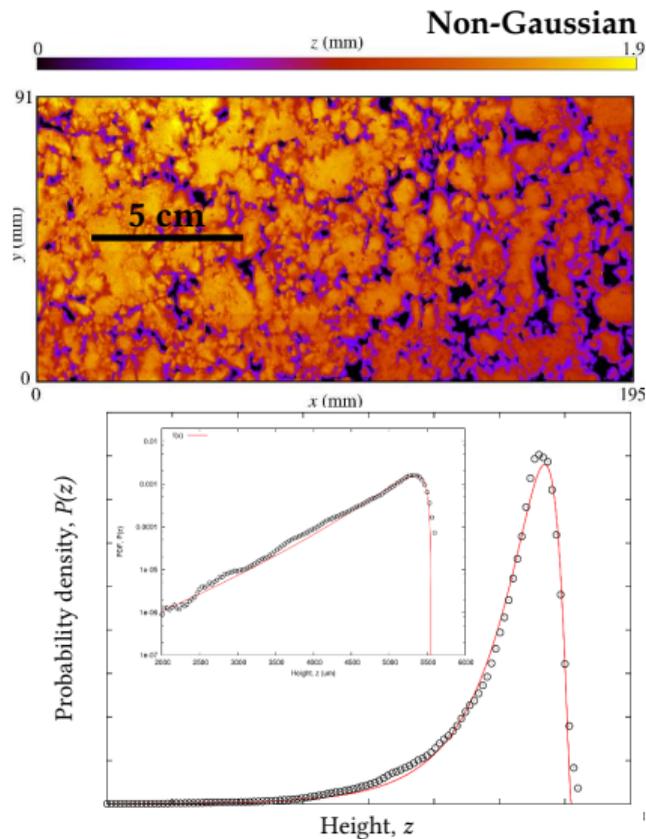
Data

- 20 countries
- 64 research groups
- 153 scientists and engineers
- 2088 measurements (FAIR data)

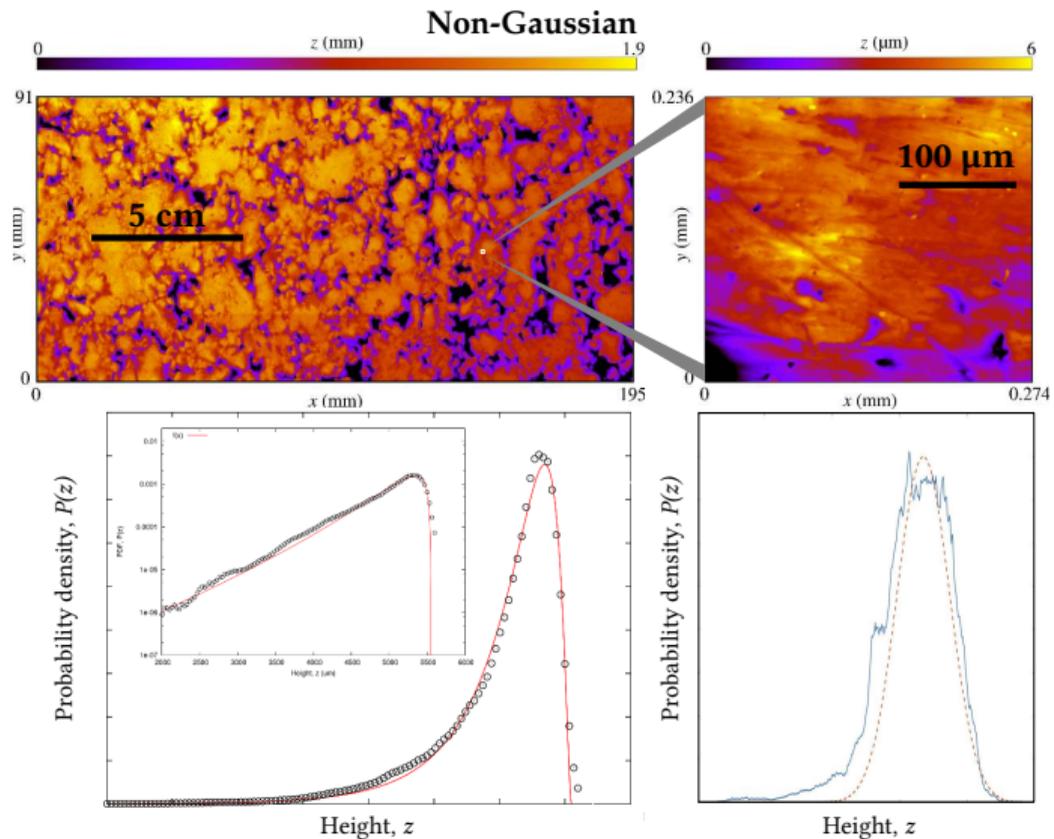


Control the short $\lambda_s = 2\pi/k_s$ and the long $\lambda_l = 2\pi/k_l$ cutoff wavelengths and H exponent

Real-life example: Asphalt roughness

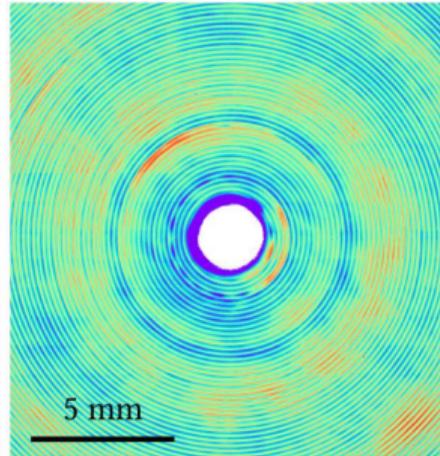


Real-life example: Asphalt roughness

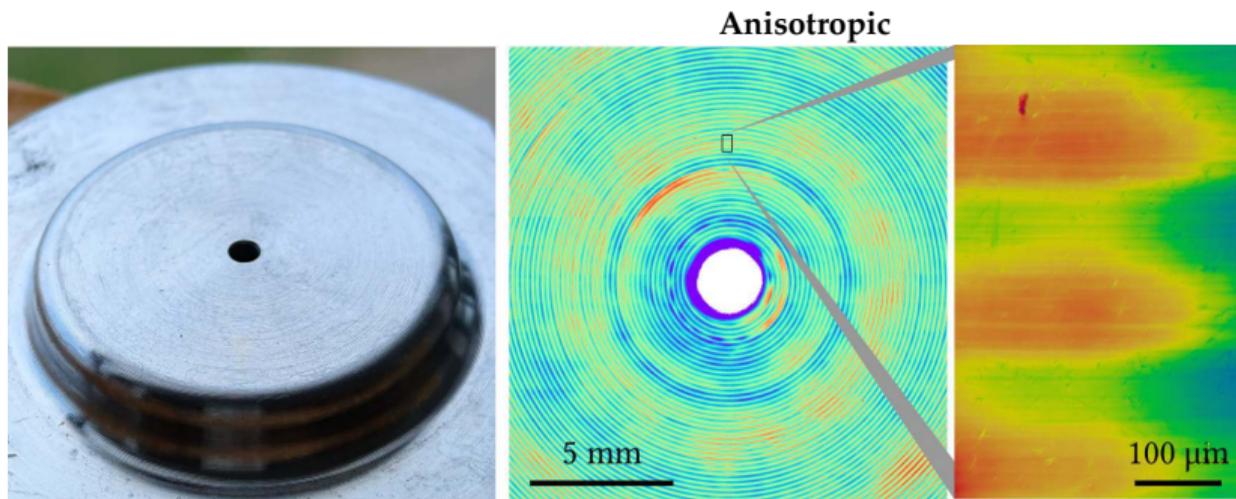


Real-life example: Turned surface

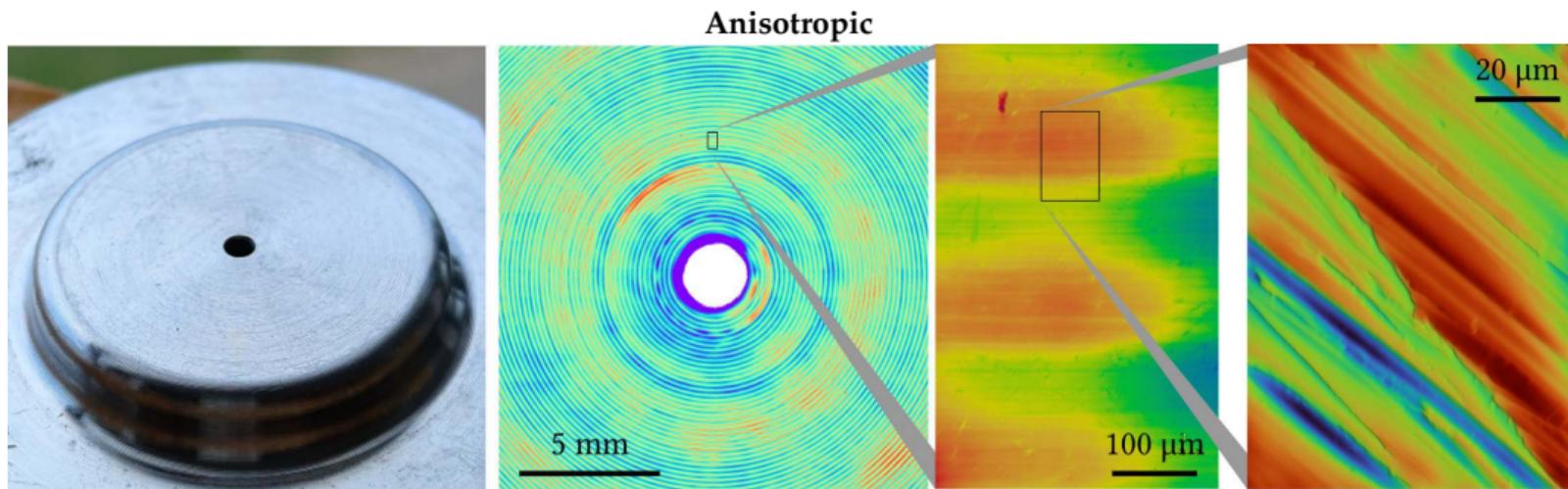
Anisotropic



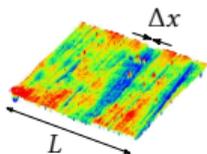
Real-life example: Turned surface



Real-life example: Turned surface



1 Scale- and sampling-sensitive characteristics

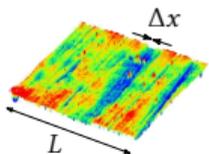


RMS roughness $S_q(L)$

RMS gradient $S_{dq}(\Delta x)$

Take-home messages

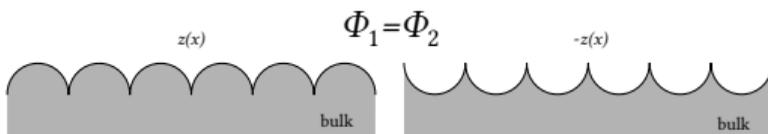
1 Scale- and sampling-sensitive characteristics



RMS roughness $S_q(L)$

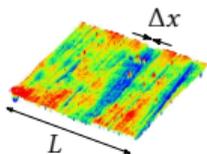
RMS gradient $S_{dq}(\Delta x)$

2 Average characteristics $\langle |\nabla z|^2 \rangle$ should be used with caution



Take-home messages

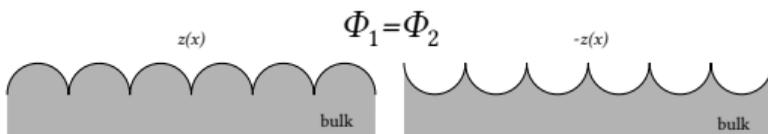
1 Scale- and sampling-sensitive characteristics



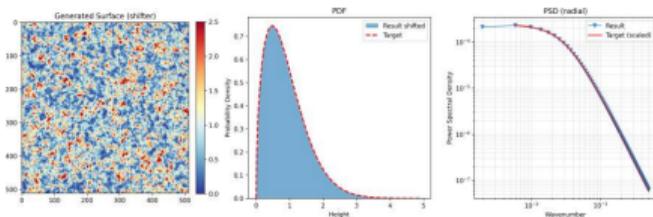
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3 PSD and PDF are independent characteristics

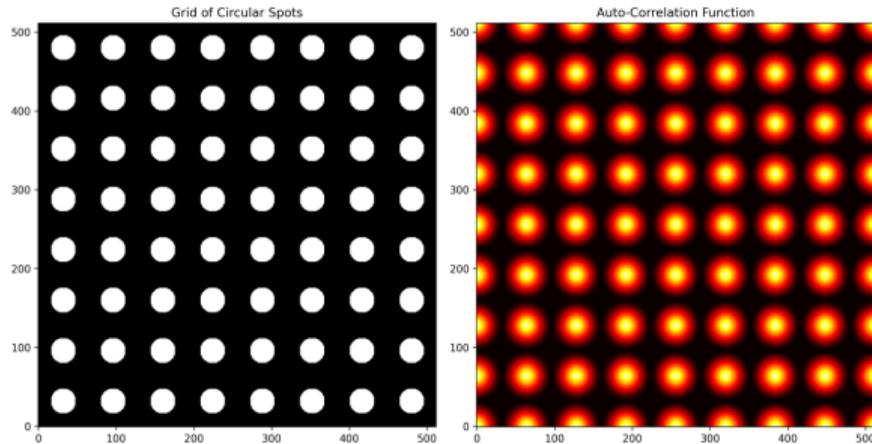


More about PSD

Autocorrelation function

■ Continuous autocorrelation function

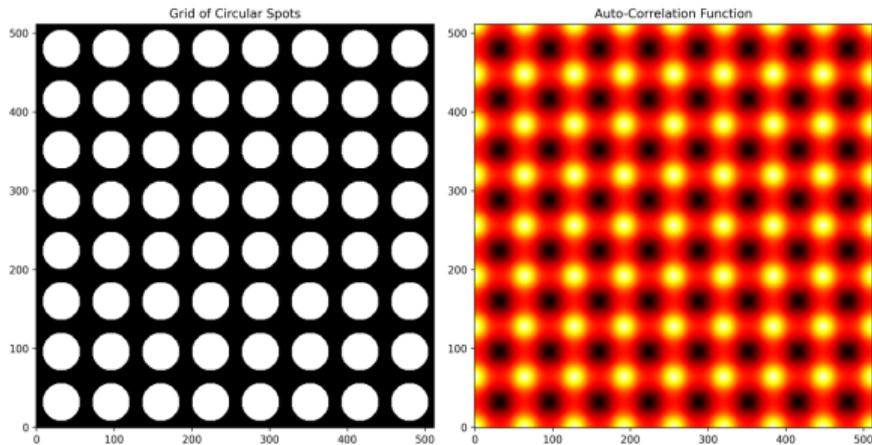
$$R(\Delta x, \Delta y) = \lim_{L \rightarrow \infty} \frac{1}{L^2} \int_0^L \int_0^L z(x + \Delta x, y + \Delta y) z(x, y) dx dy$$



Autocorrelation function

■ Continuous autocorrelation function

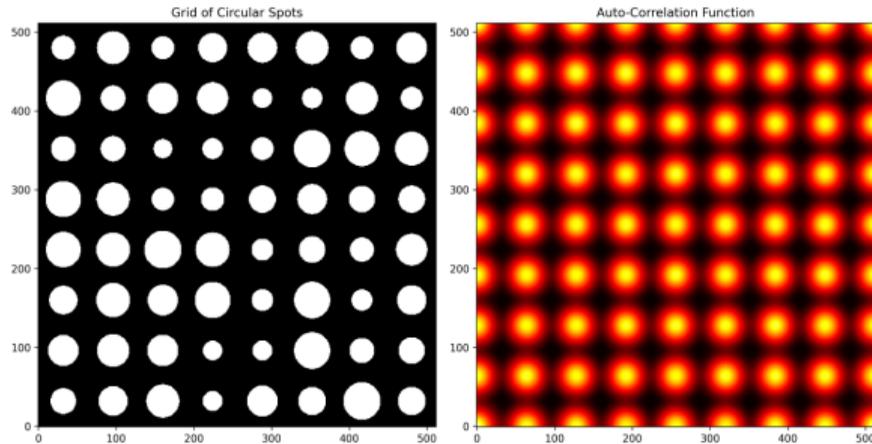
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Autocorrelation function

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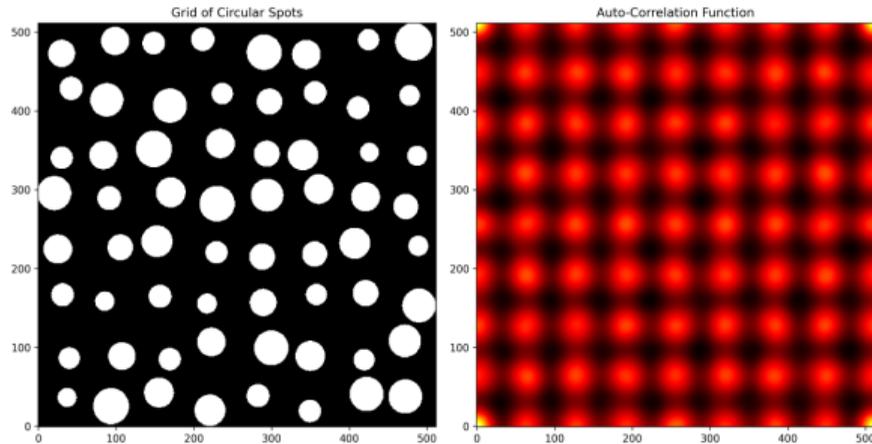
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Autocorrelation function

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$$R(\Delta x, \Delta y) = \lim_{L \rightarrow \infty} \frac{1}{L^2} \int_0^L \int_0^L z(x + \Delta x, y + \Delta y) z(x, y) dx dy$$



Power spectral density (PSD)

- Fourier Transform: $\hat{f}(k) = \frac{1}{2\pi} \int_{-\infty}^{\infty} f(x) \exp(-ikx) dx$ where x is the spatial coordinate, $k = 2\pi/\lambda$ is the wavenumber and λ is the wavelength.
- PSD is the Fourier Transform of R

$$\Phi(k_x, k_y) \equiv \hat{R}(k_x, k_y) = \text{FT} [z(x + \Delta x, y + \Delta y) * z(x, y)]$$

- Using convolution theorem

$$\Phi(k_x, k_y) = \hat{z}(k_x, k_y) \hat{z}^*(k_x, k_y) = \hat{z}^2(k_x, k_y)$$

- Interpretation: energy distribution by frequencies
- Usage: signal analysis, seismology, microstructure characterization, roughness.

Spectral moments

- Spectral moment $m_{pq}, p, q \in \mathbb{N}$:

$$m_{pq} = \iint_{-\infty}^{\infty} k_x^p k_y^q \Phi(k_x, k_y) dk_x dk_y$$

- Generalized spectral moment $m_{pq}, p, q \in \mathbb{R}^+$

- For isotropic surface: $m_2 = m_{20} = m_{02}, \quad m_4 = 3m_{22} = m_{40} = m_{04}$

- Averaging:

$$m_2 = \frac{m_{20} + m_{02}}{2}, \quad m_4 = \frac{m_{40} + 3m_{22} + m_{04}}{3}$$

- Physical meaning:

Height variance¹: $m_0 = \langle (z - \langle z \rangle)^2 \rangle$

Gradient variance: $2m_2 = \langle (\nabla z - \langle \nabla z \rangle)^2 \rangle$

Curvature variance: $m_4 = \langle (\nabla \cdot \nabla z - \langle \nabla \cdot \nabla z \rangle)^2 \rangle$

[1] Longuet-Higgins, M. S. (1957). The statistical analysis of a random, moving surface. Phil. Trans. Royal Society of London. Series A 249(966):321-387.

[2] Nayak, P. R. (1971). Random Process Model of Rough Surfaces. Journal of Lubrication Technology, 93(3):398-407

¹Variance is the square of the standard deviation

Summary

- Fractal (self-affine) roughness
- Power spectral density (PSD)
 $\Phi(k) \sim k^{-2(H+1)}$
 k is a wavenumber,
 H is the Hurst exponent.
- **Isotropic**/anisotropic surfaces
- **Gaussian**/non-Gaussian height distribution $P(h)$

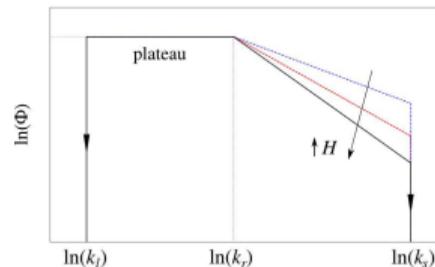
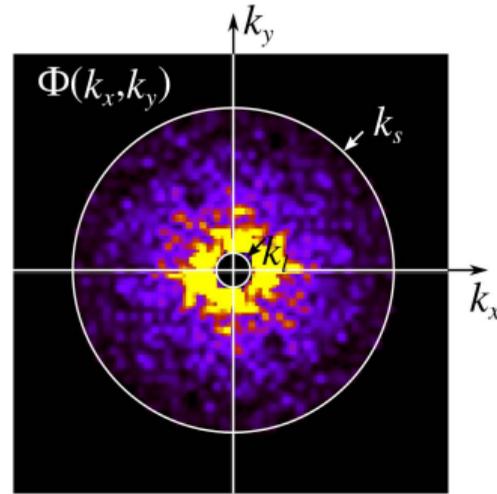


Fig. 3D and radial power spectral densities

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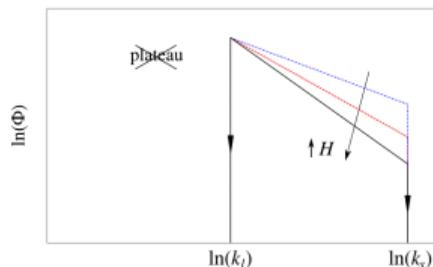
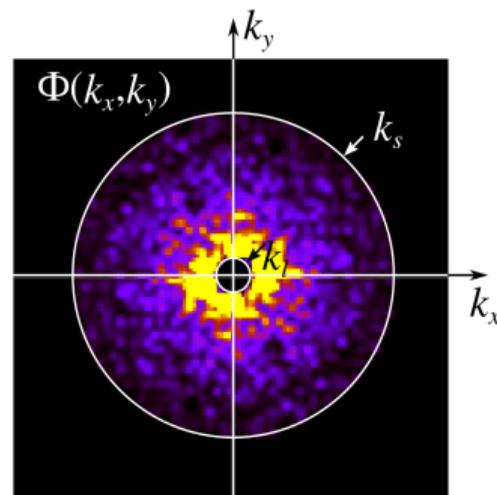


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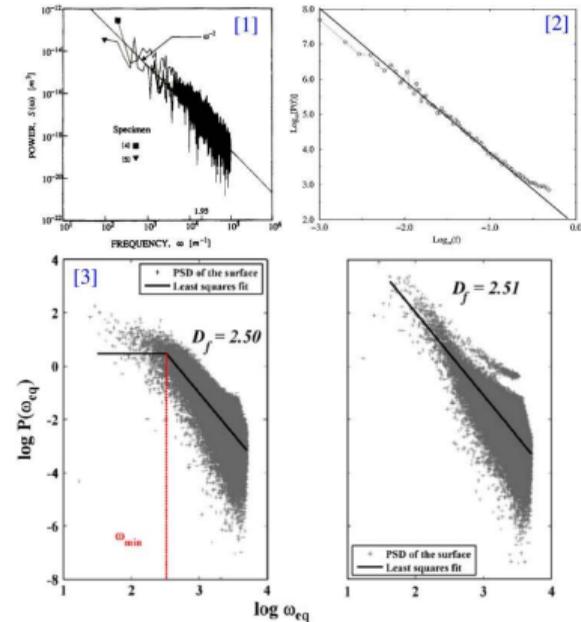


Fig. Power spectral density, measurements

- [1] Majumdar, Tien, Wear 136 (1990)
- [2] Schmittbuhl, Jørgen Måløy, Phys. Rev. Lett. 78 (1997)
- [3] Vallet, Lasseux, Sainot, Zahouani, Tribol. Int. 42 (2009)

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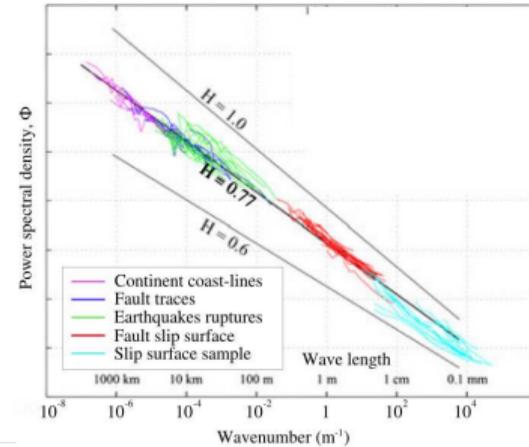


Fig. Power spectral density, geological scales

Adapted from

[4] Renard, Candela, Bouchaud, *Geophys. Res. Lett.* 40 (2013)

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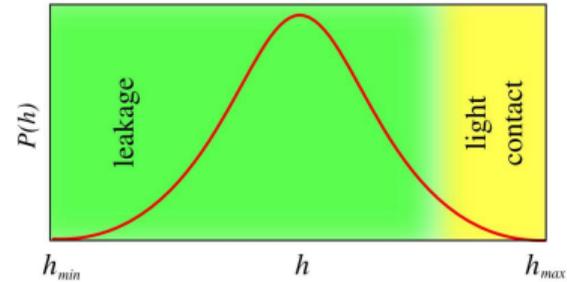


Fig. Height distribution $P(h)$

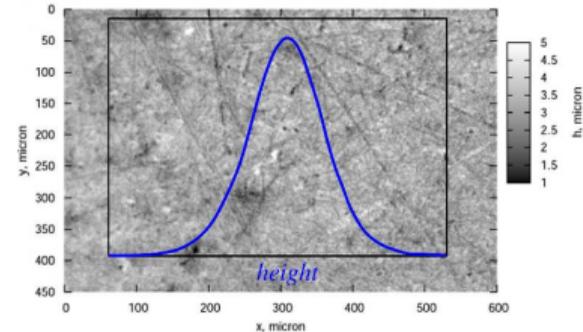


Fig. Height distribution of a polished metal surface

Summary

- Fractal (self-affine) roughness

- Power spectral density (PSD)

$$\Phi(k) \sim k^{-2(H+1)}$$

k is a wavenumber,

H is the Hurst exponent.

- Isotropic/anisotropic surfaces

- Gaussian/non-Gaussian height distribution $P(h)$

- Characteristics:

- $\sqrt{\langle z^2 \rangle}$ - rms heights
- $\sqrt{\langle |\nabla z|^2 \rangle}$ - rms slope (surface gradient)
- $\alpha = m_{00}m_{40}/m_{20}^2$ - breadth of the spectrum (Nayak's parameter^[B]),

- Random process theory

[A] Longuet-Higgins, Philos. Trans. R. Soc. A 250:157 (1957)

[B] Nayak, J. Lub. Tech. (ASME) 93:398 (1973)

[C] Greenwood, Wear 261: 191 (2006)

[D] Borri, Paggi, J. Phys. D Appl Phys 48:045301 (2015)

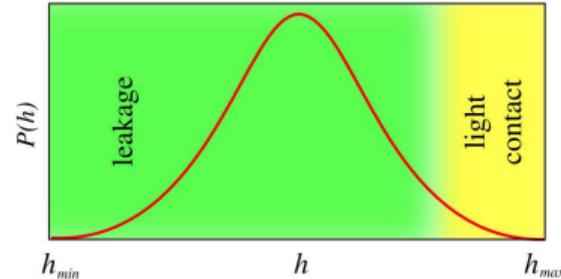


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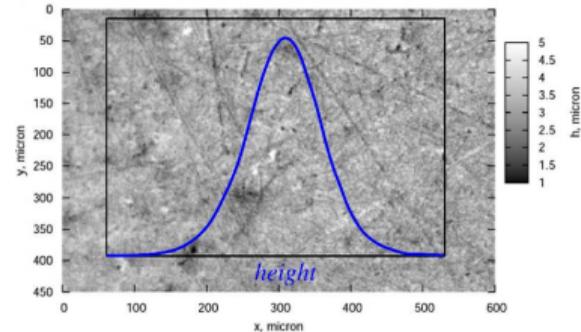


Fig. Height distribution of a polished metal surface

Fractals

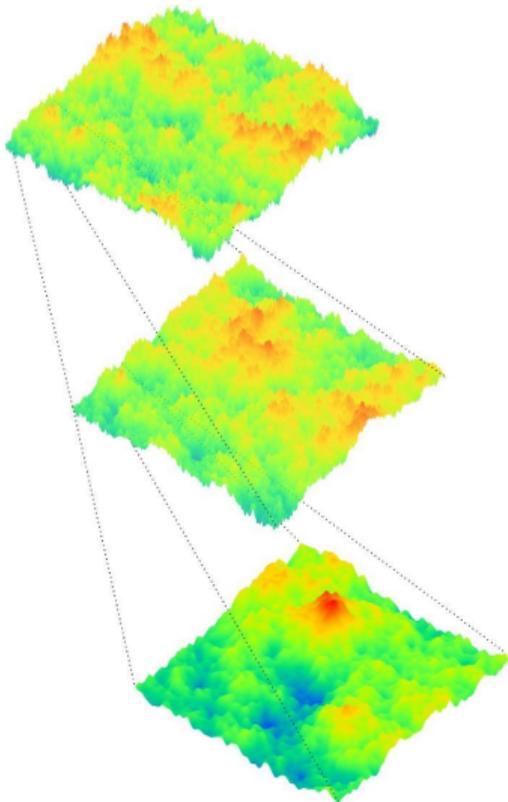


Fig. Example of a rough surface for $H = 0.3$

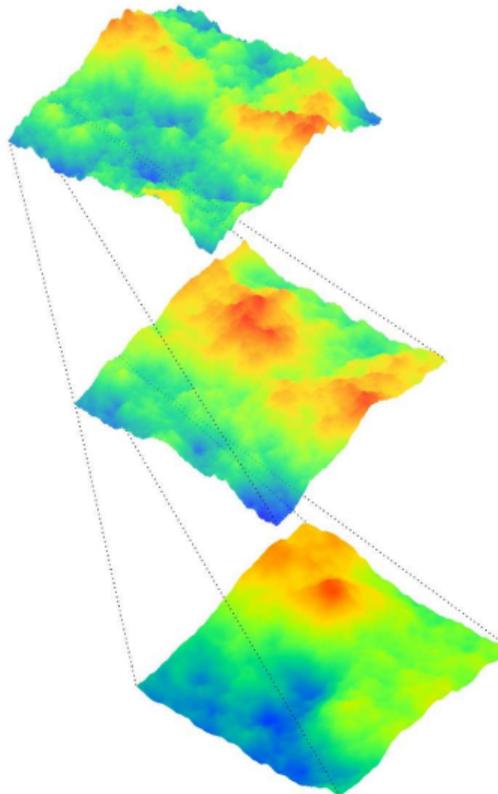
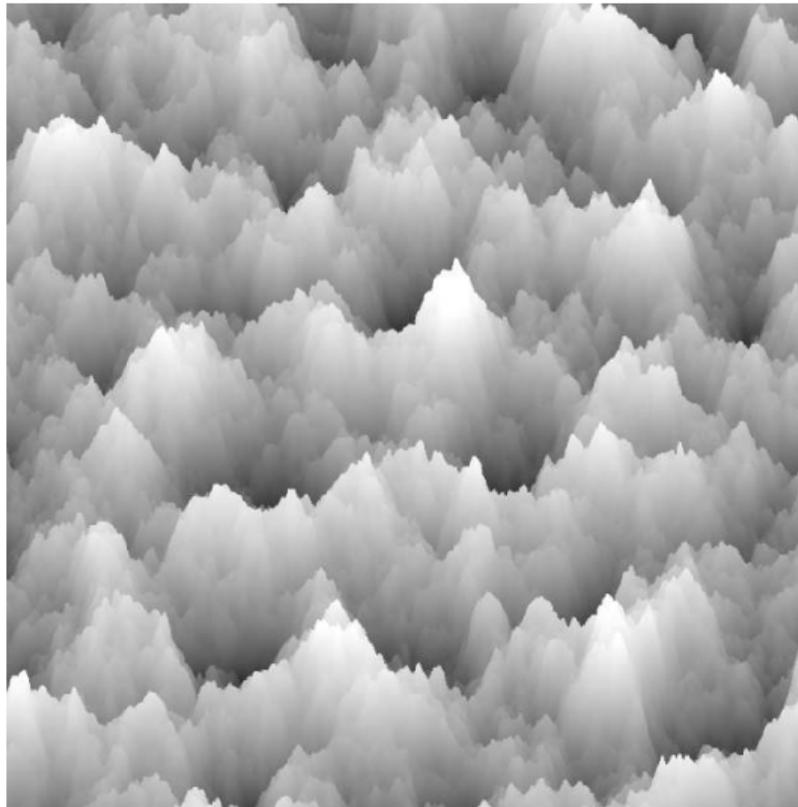


Fig. Example of a rough surface for $H = 0.8$

NB: the Hurst exponent H and the fractal dimension D in 2D space are interconnected via $D = 3 - H$



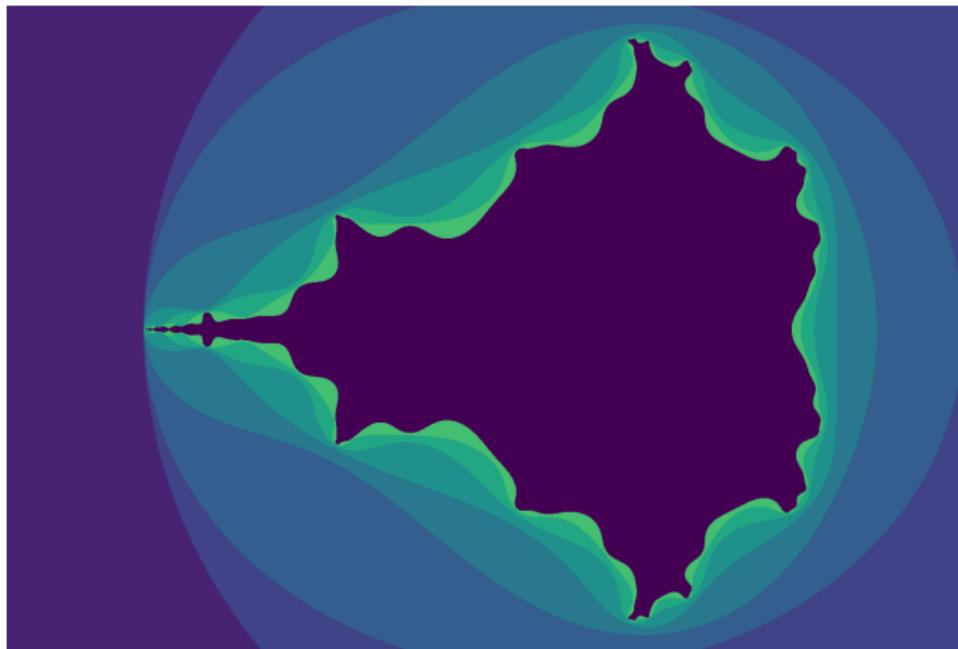
Flight over a rough surface



Romanesco broccoli

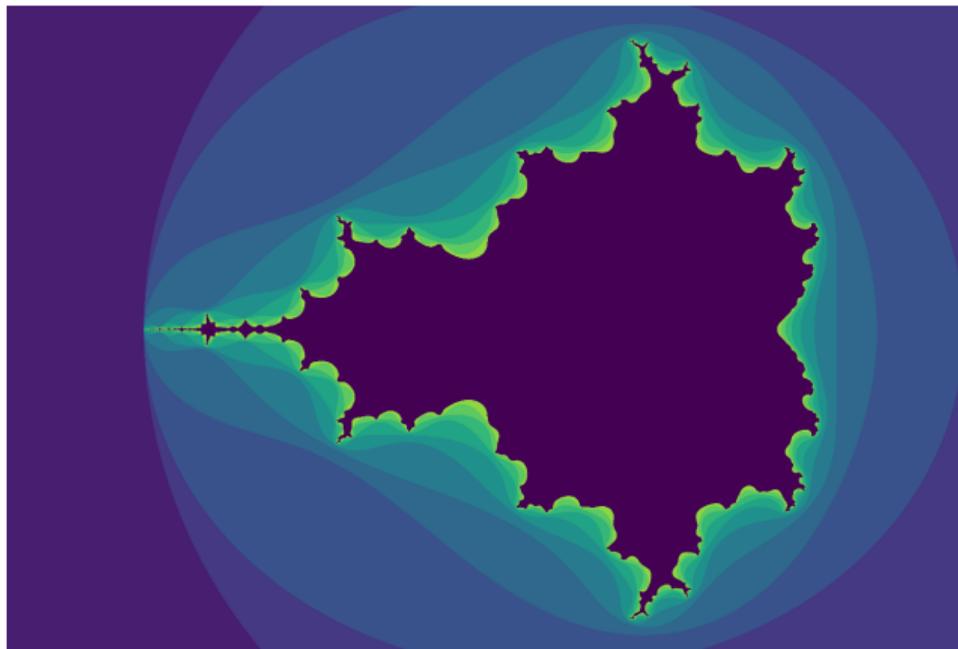
- Mandelbrot set (not a fractal)
- Recursive function

$$z_{i+1} = z_i^2 + z, \quad z \in \mathbb{C}$$



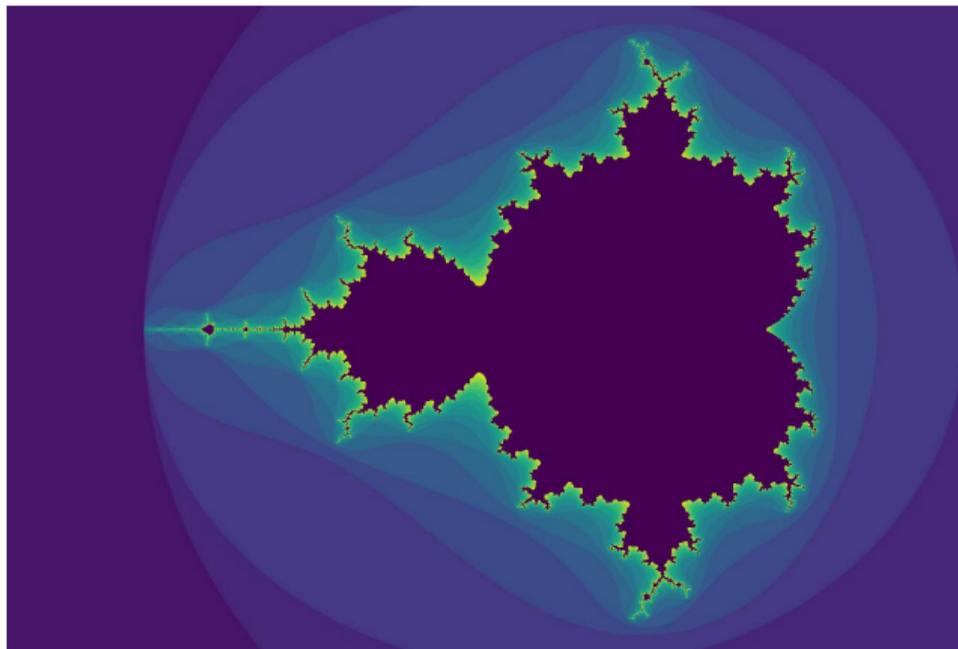
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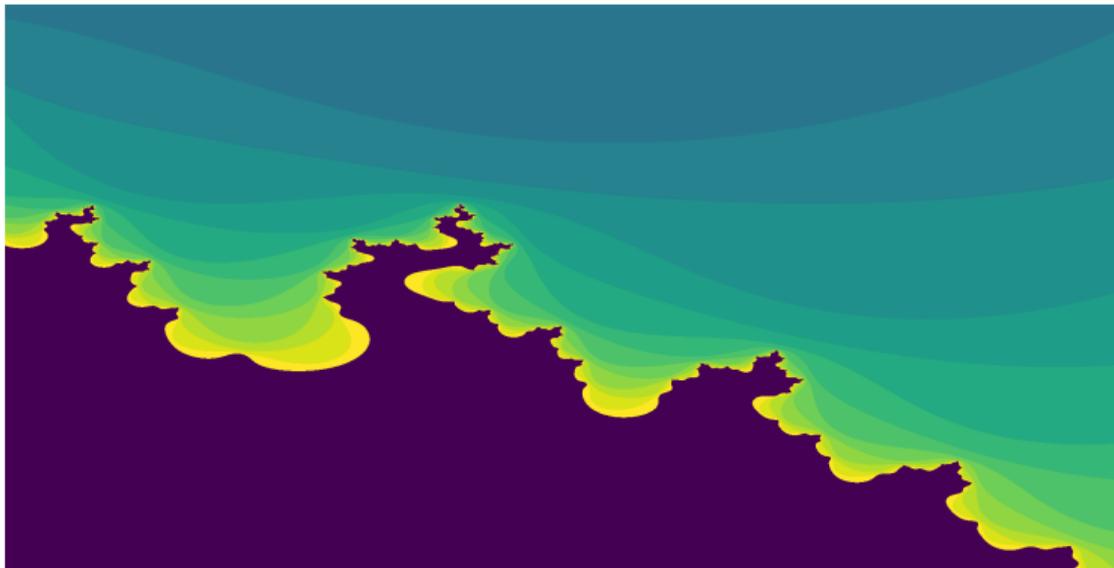
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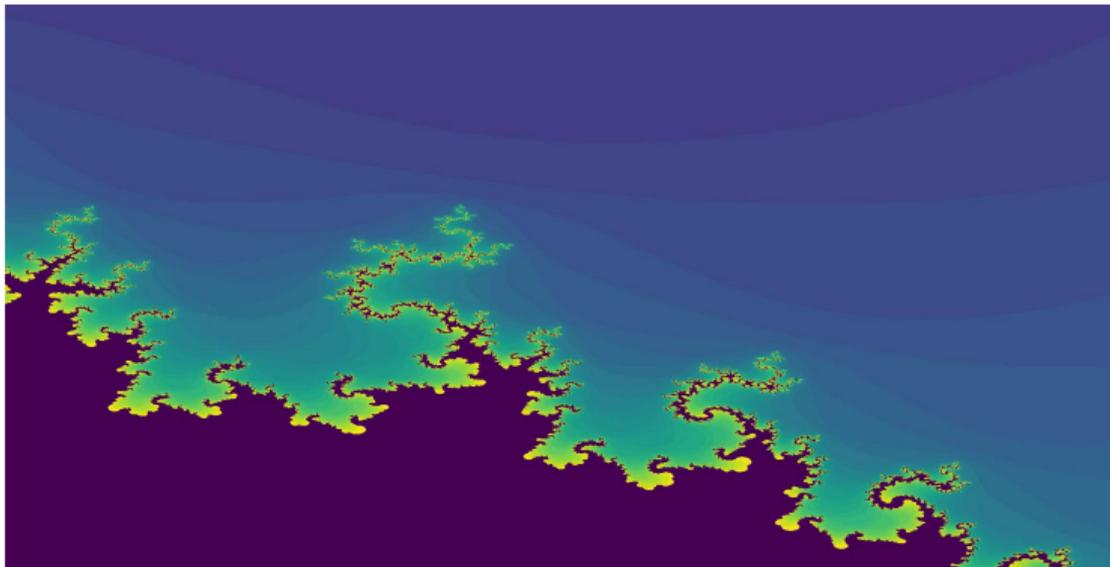
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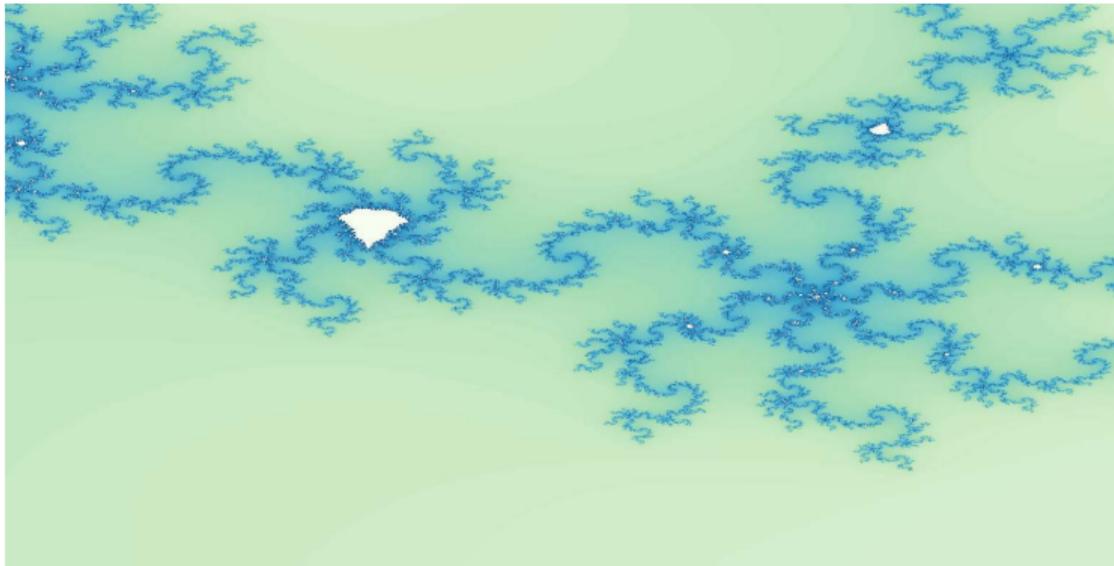
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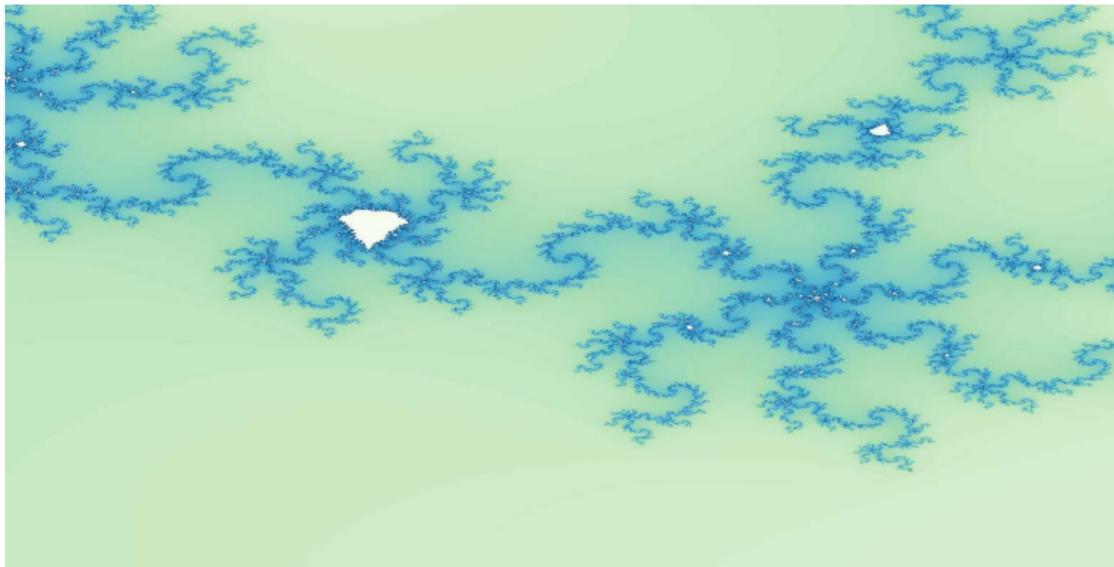
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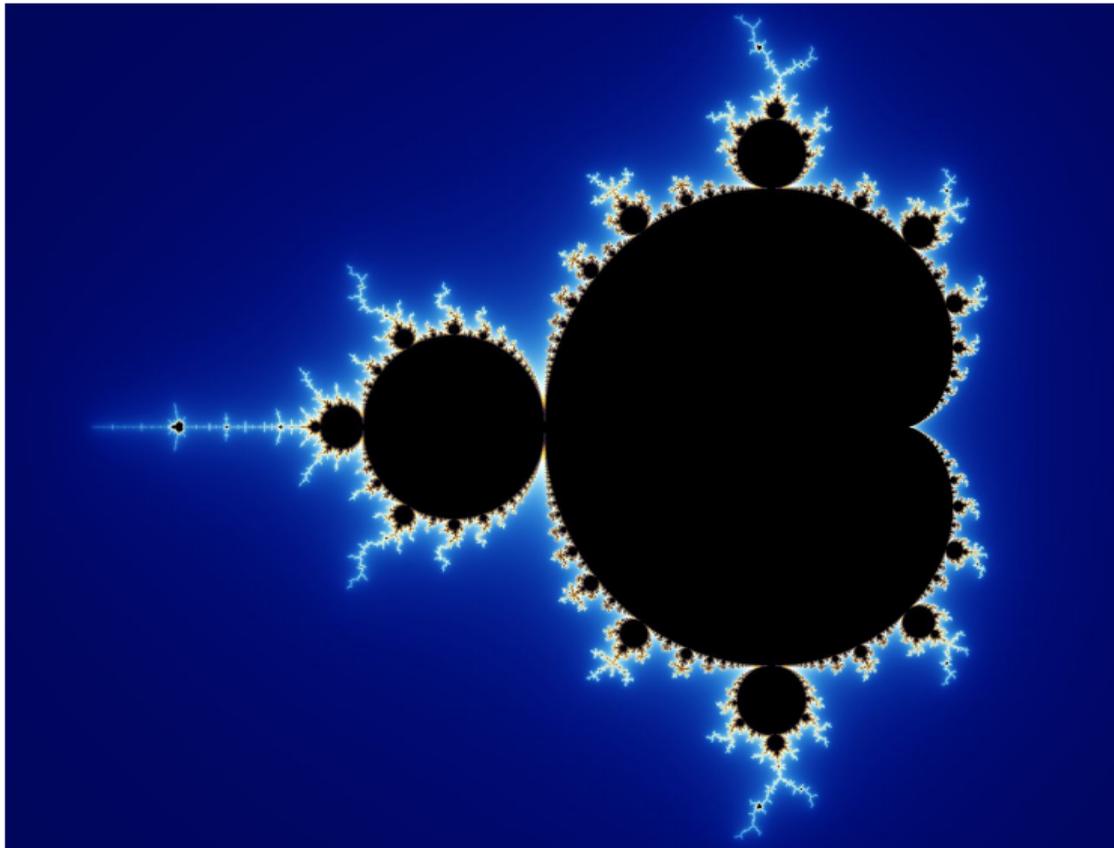
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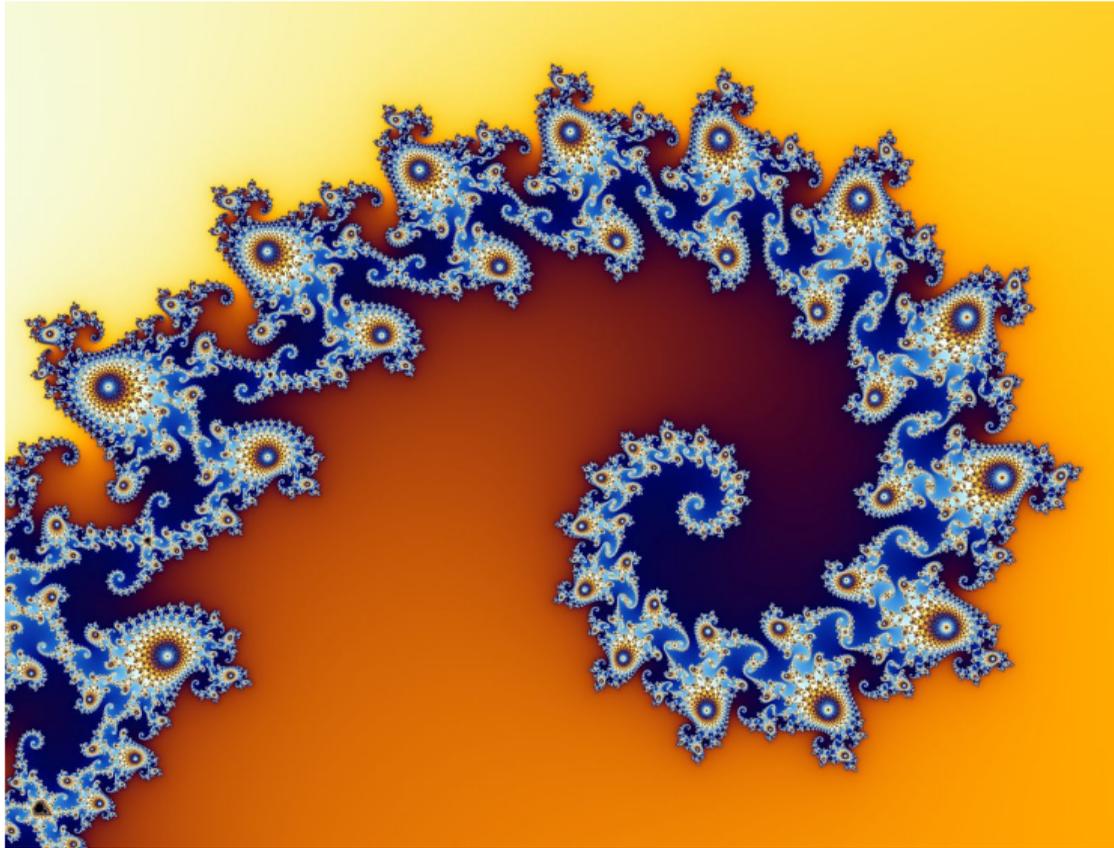
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$$z_{i+1} = z_i^2 + z, \quad z \in \mathbb{C}$$

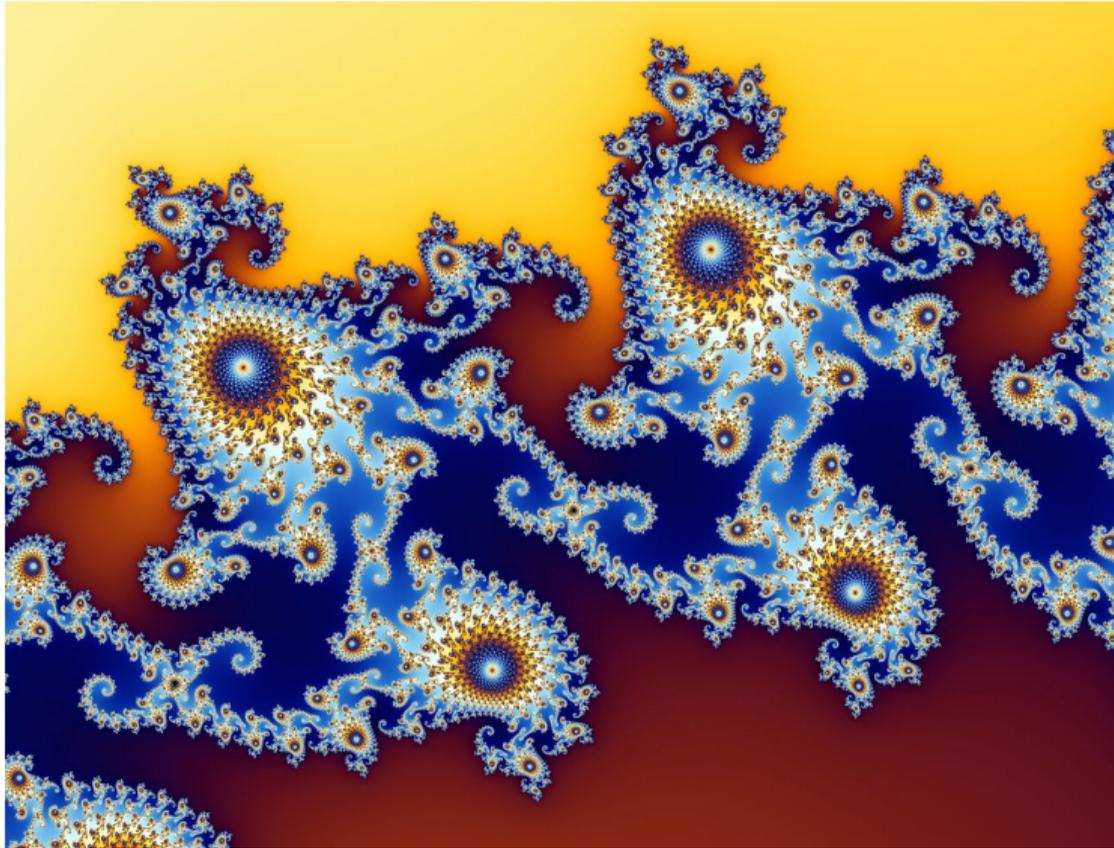




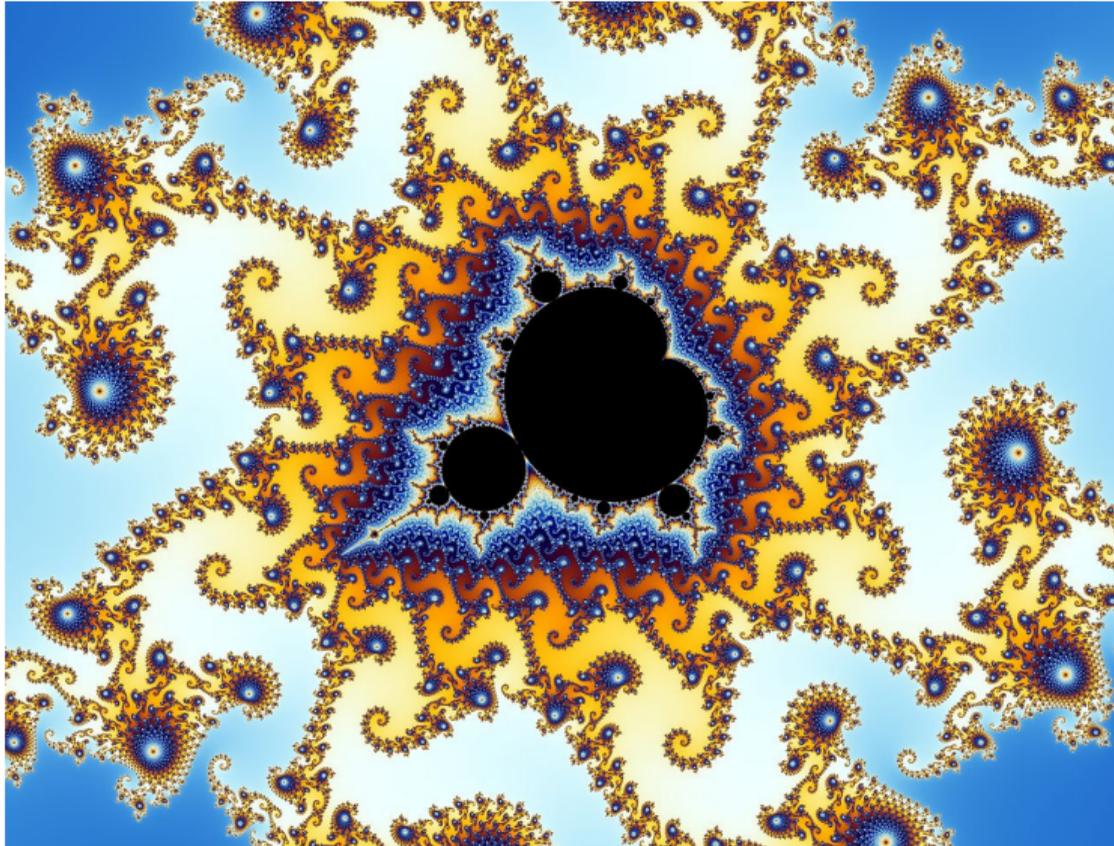
Mandelbrot set (Wikipedia)



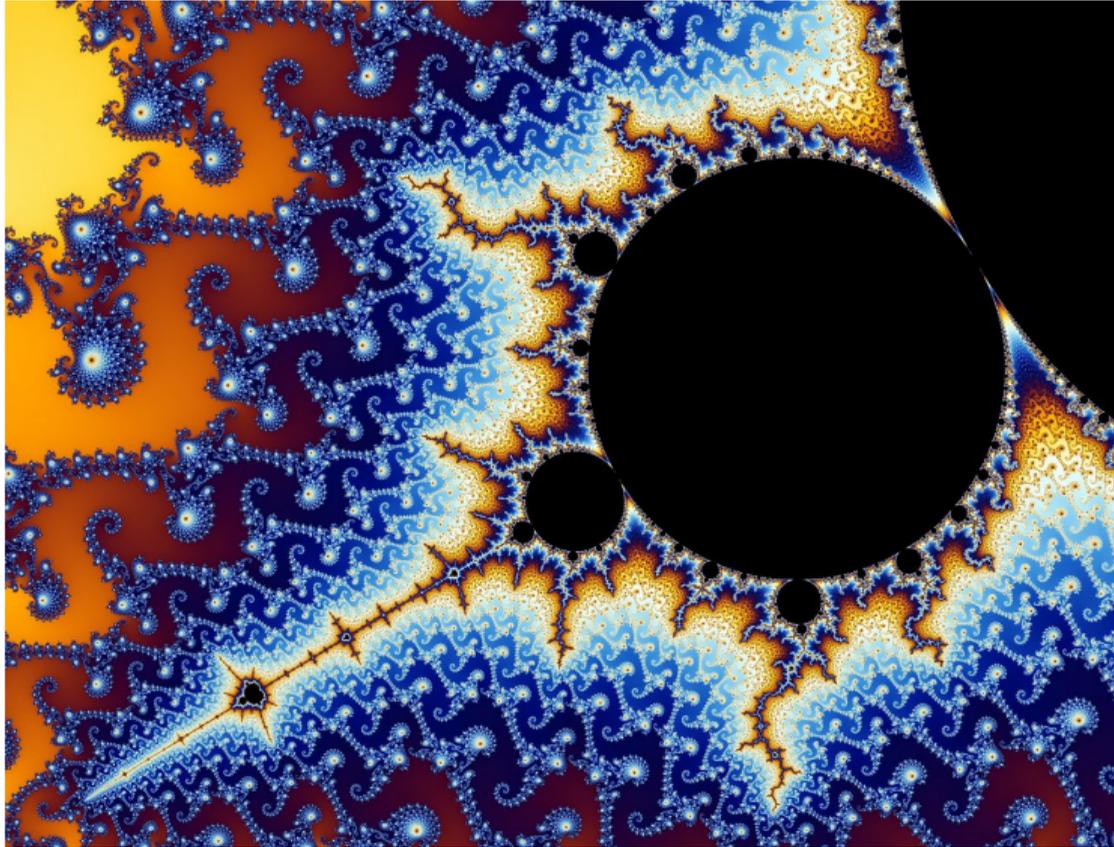
Element of Mandelbrot set (Wikipedia)



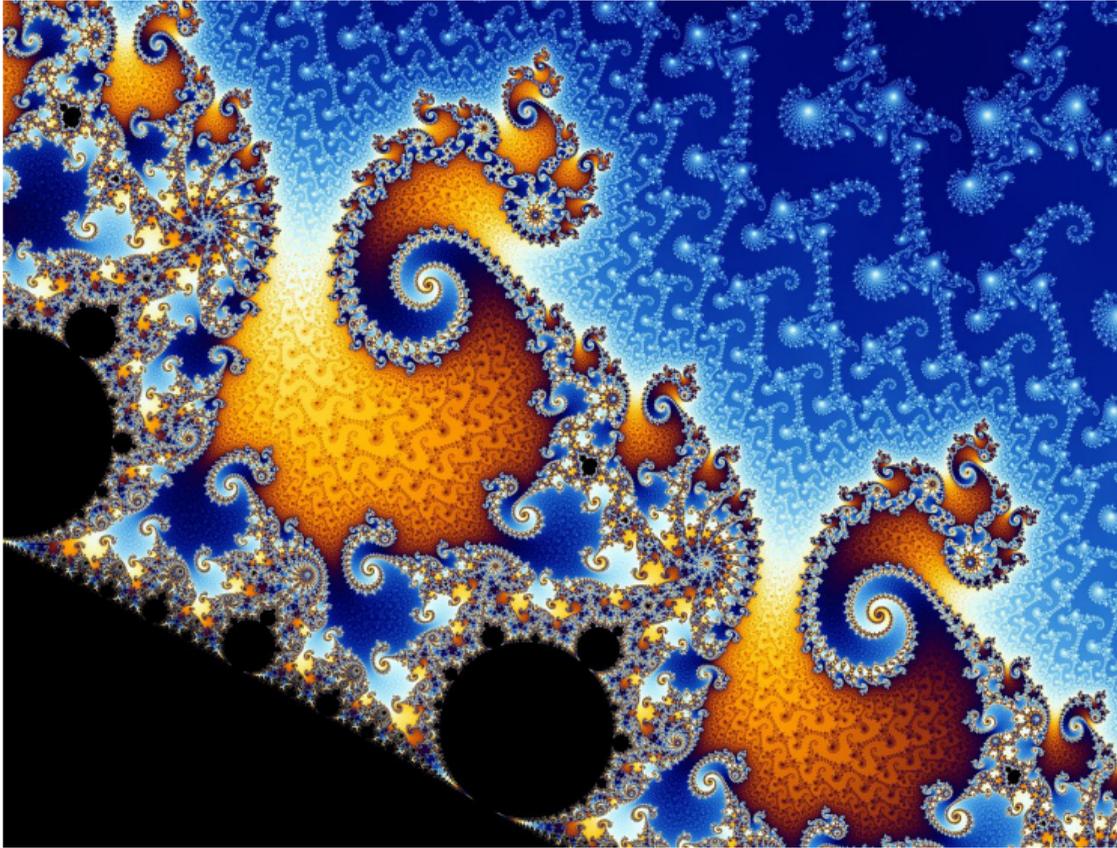
Element of Mandelbrot set (Wikipedia)



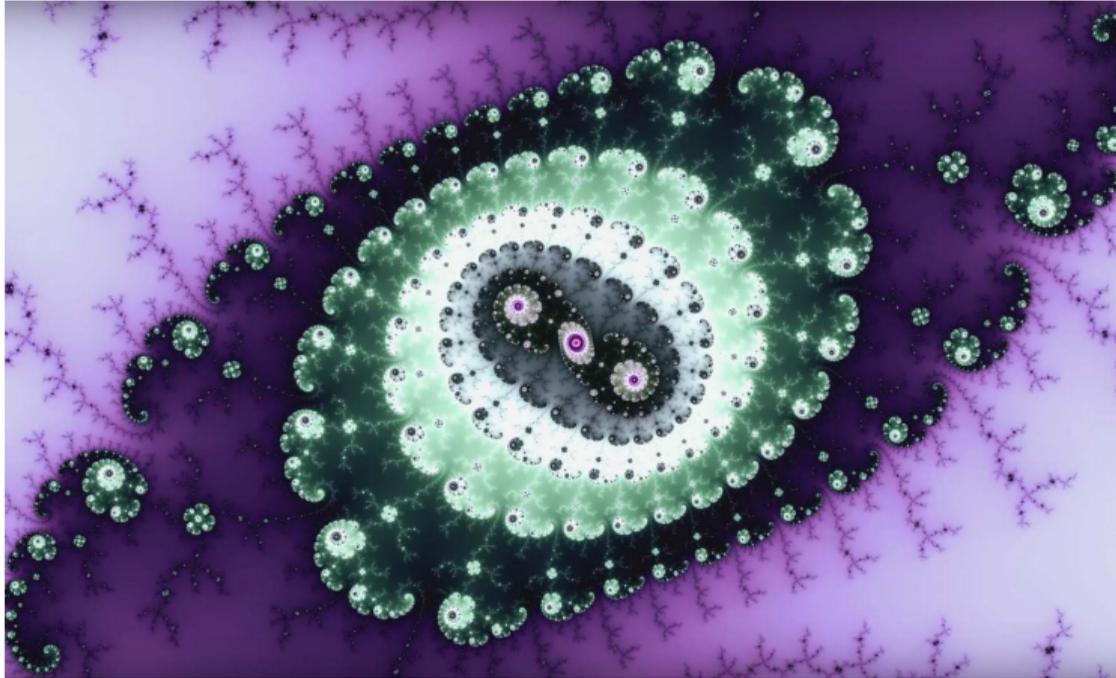
Element of Mandelbrot set (Wikipedia)



Element of Mandelbrot set (Wikipedia)



Element of Mandelbrot set (Wikipedia)



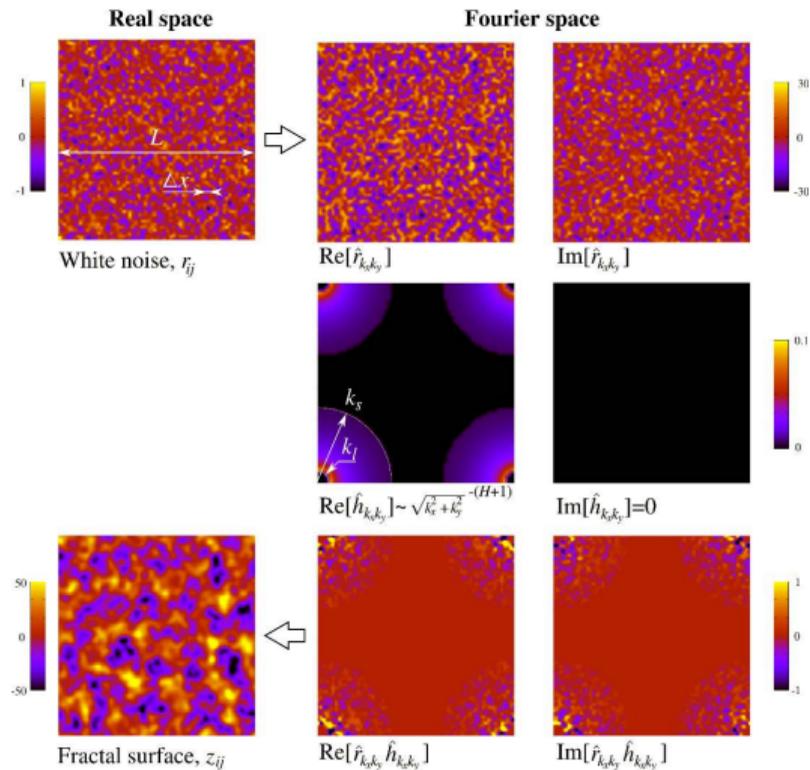
See animation

<https://youtu.be/pCpLWbHVNhk>

70 minutes of 4K "Eye of the Universe - Mandelbrot Fractal Zoom" e^{1091}

Effect of Model Parameters

Synthesized rough surfaces



[1] Y. Z. Hu and K. Tonder, Int. J. Machine Tools Manuf. 32, 83 (1992)

Effect of parameters: illustration

- Effect of the high frequency cutoff k_s

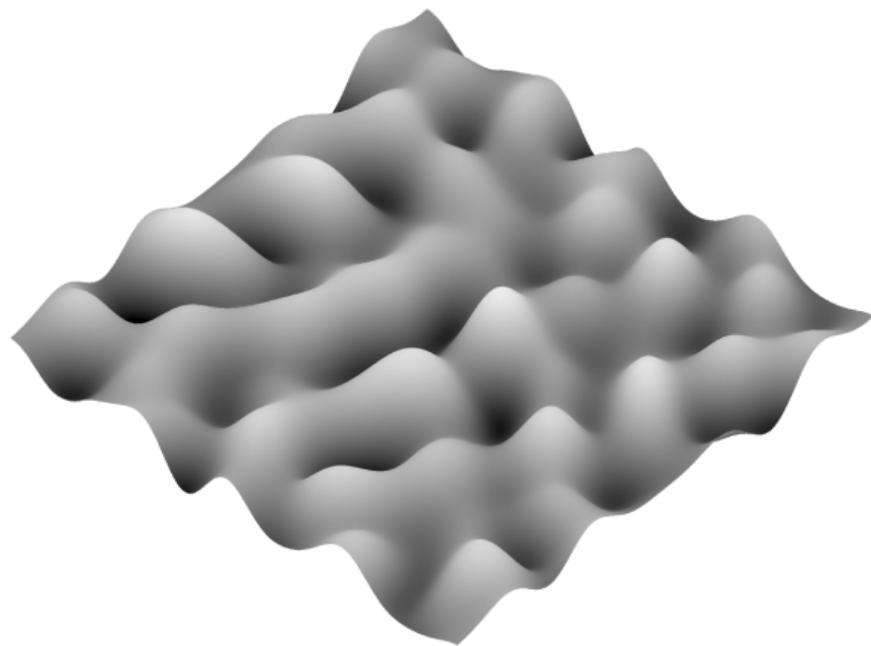
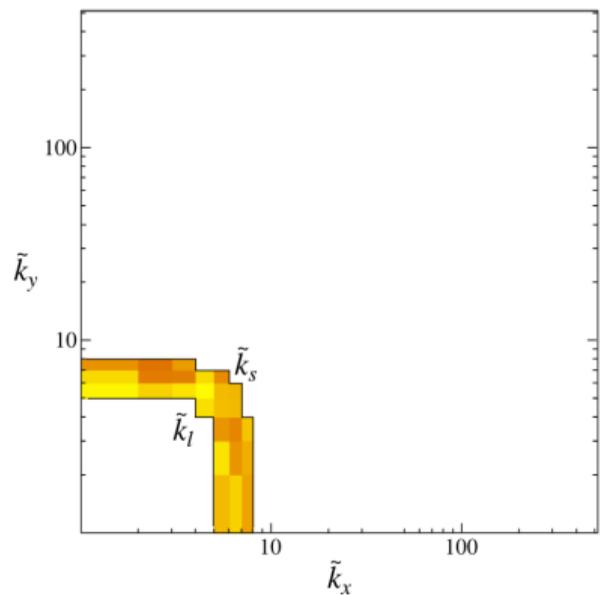


Fig. Power spectral density (Fourier space)
and corresponding rough surface (real space) for
 $k_l = 4, \quad k_s = 8$

Effect of parameters: illustration

- Effect of the high frequency cutoff k_s

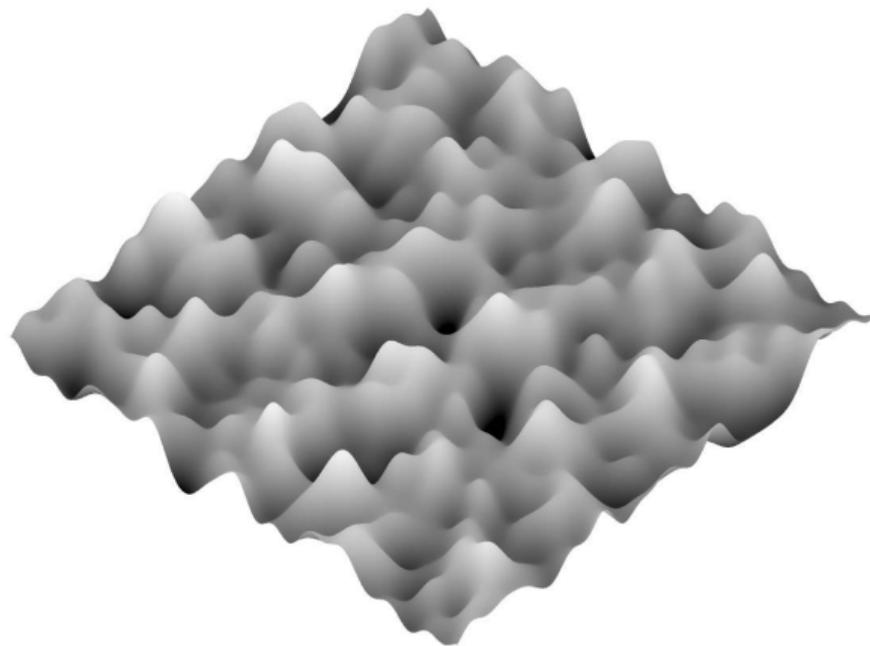
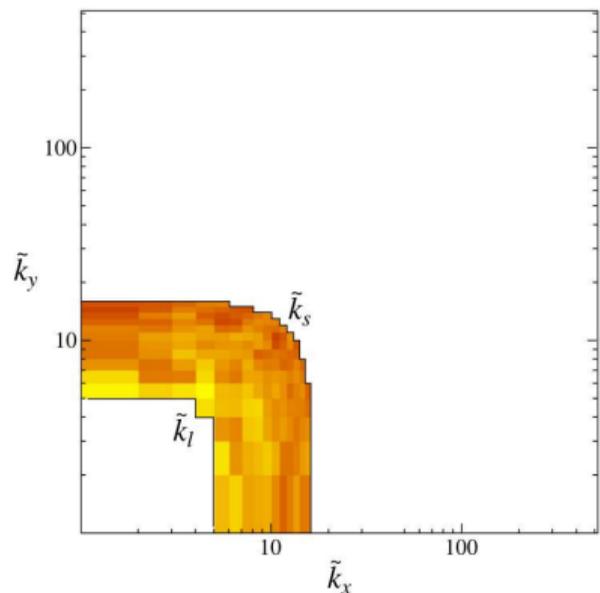


Fig. Power spectral density (Fourier space)
and corresponding rough surface (real space) for
 $k_l = 4, \quad k_s = 16$

Effect of parameters: illustration

- Effect of the high frequency cutoff k_s

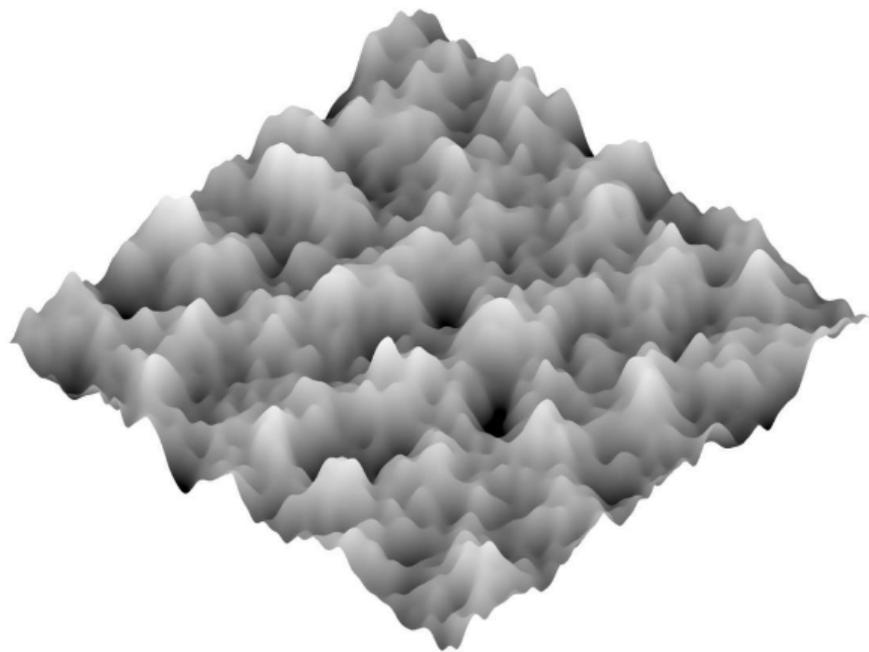
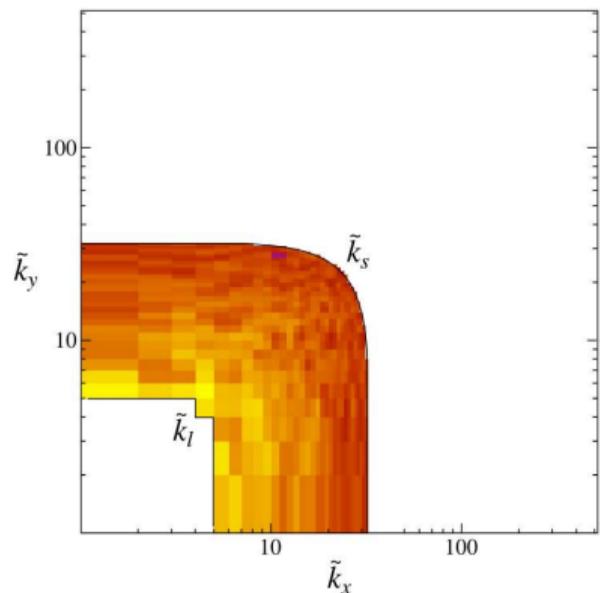


Fig. Power spectral density (Fourier space)
and corresponding rough surface (real space) for
 $k_l = 4, \quad k_s = 32$

Effect of parameters: illustration

- Effect of the high frequency cutoff k_s

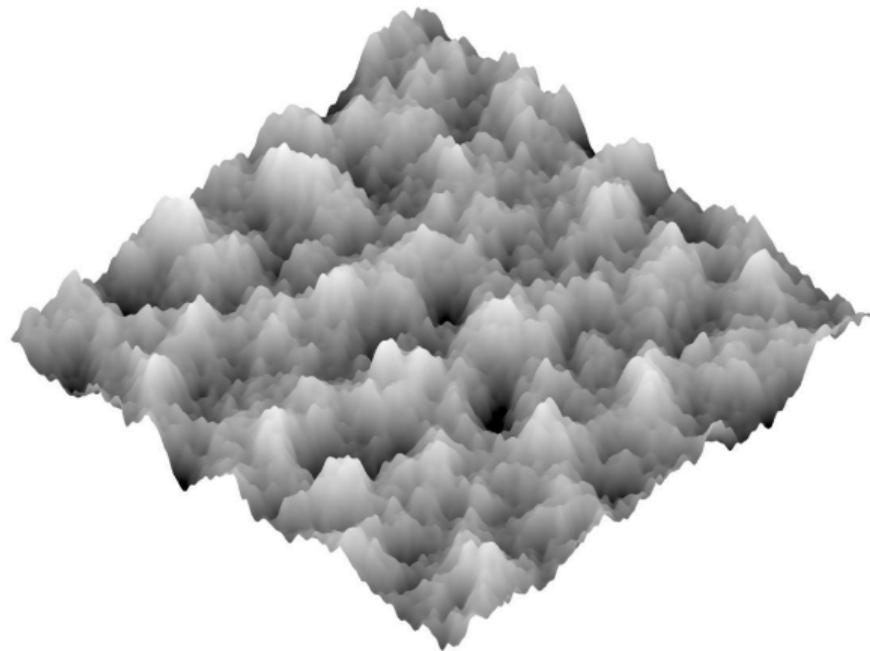
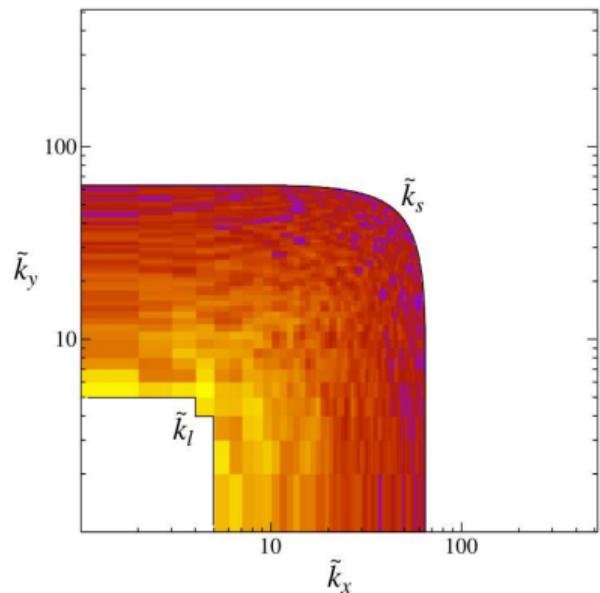


Fig. Power spectral density (Fourier space)
and corresponding rough surface (real space) for
 $k_l = 4$, $k_s = 64$

Effect of parameters: illustration

- Effect of the high frequency cutoff k_s

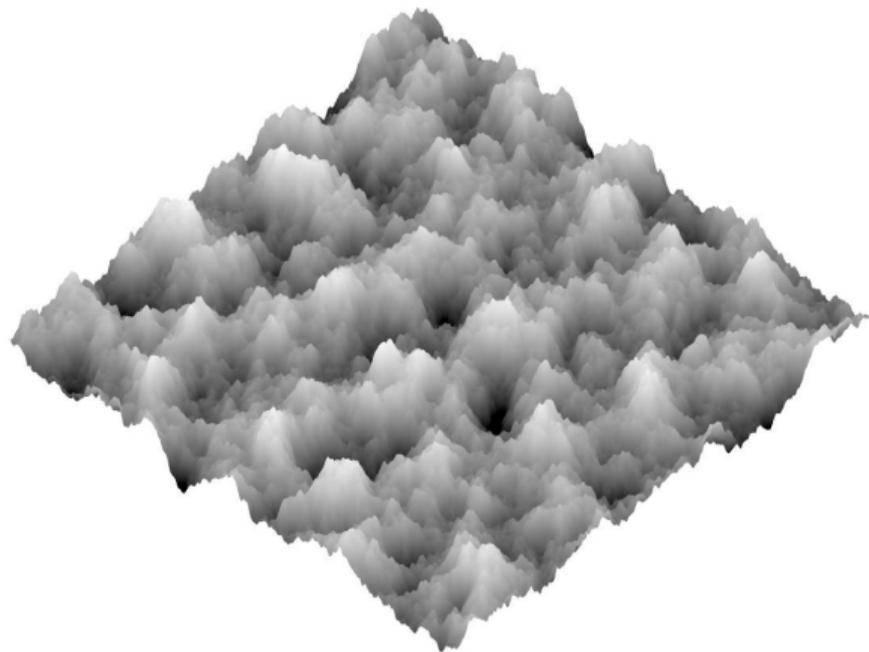
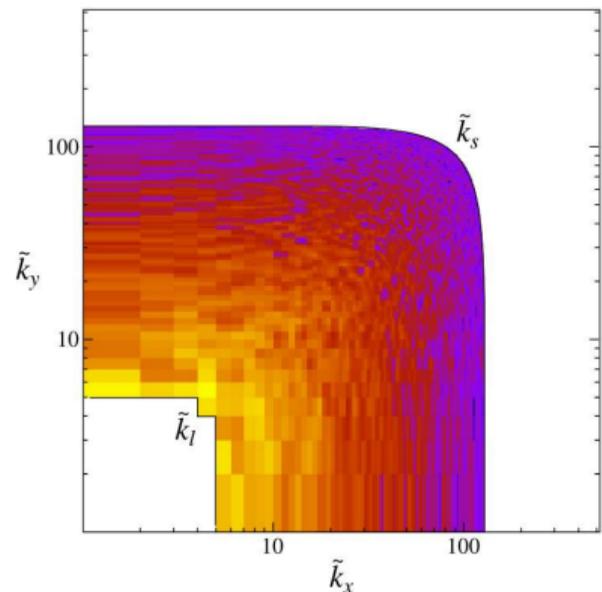


Fig. Power spectral density (Fourier space)
and corresponding rough surface (real space) for
 $k_l = 4, \quad k_s = 128$

Effect of parameters: illustration

- Effect of the lower frequency cutoff k_l for $k_s/k_l = \text{const}$

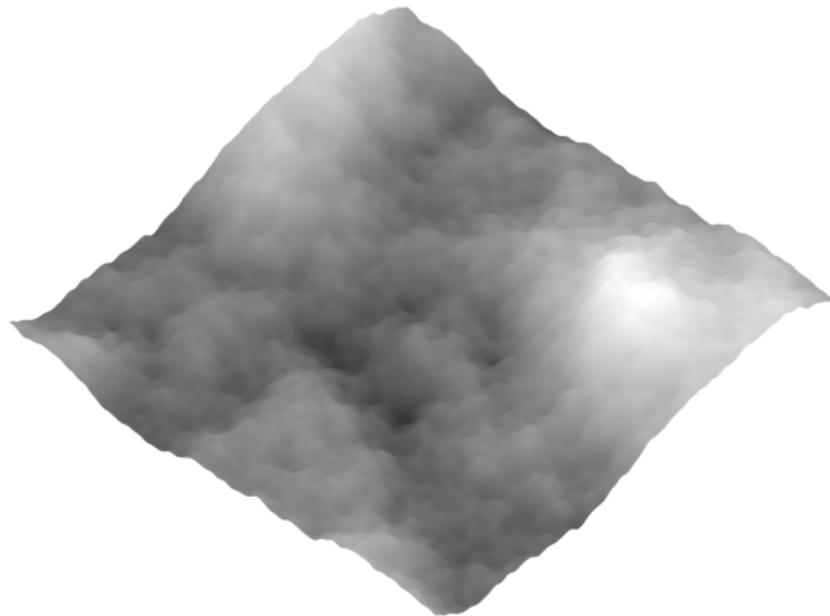
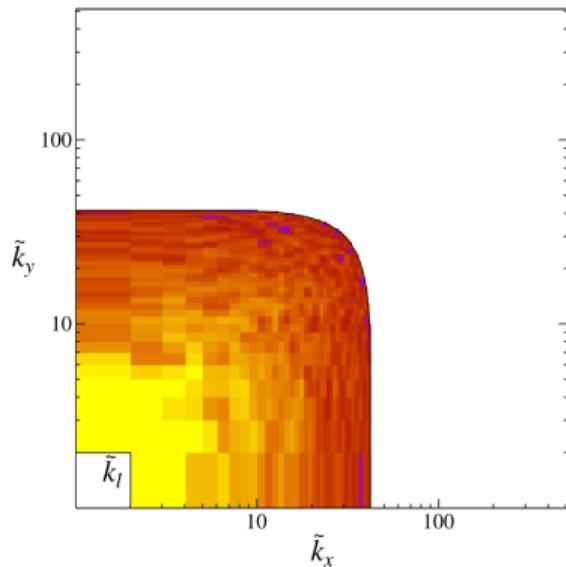


Fig. Power spectral density (Fourier space)
and corresponding rough surface (real space) for
 $k_l = 1, k_s = 43$

Effect of parameters: illustration

- Effect of the lower frequency cutoff k_l for $k_s/k_l = \text{const}$

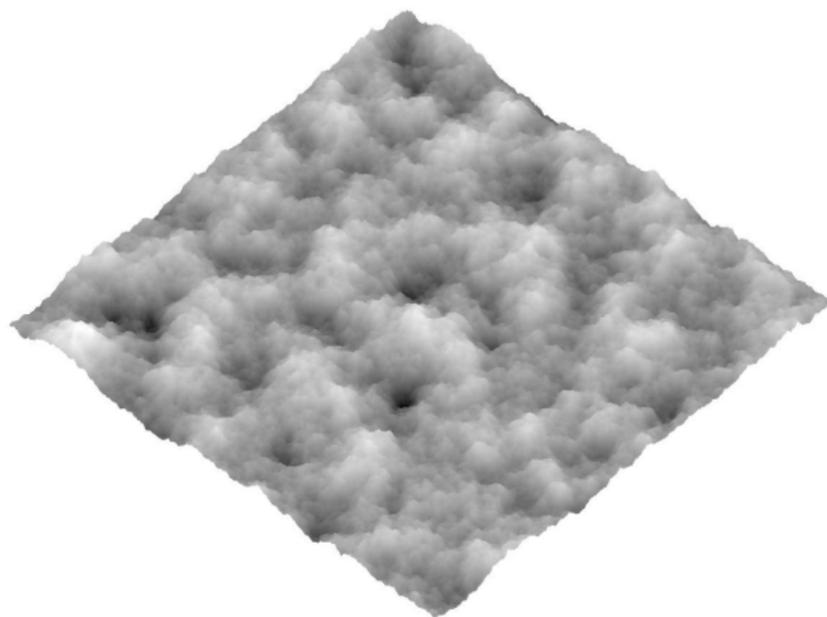
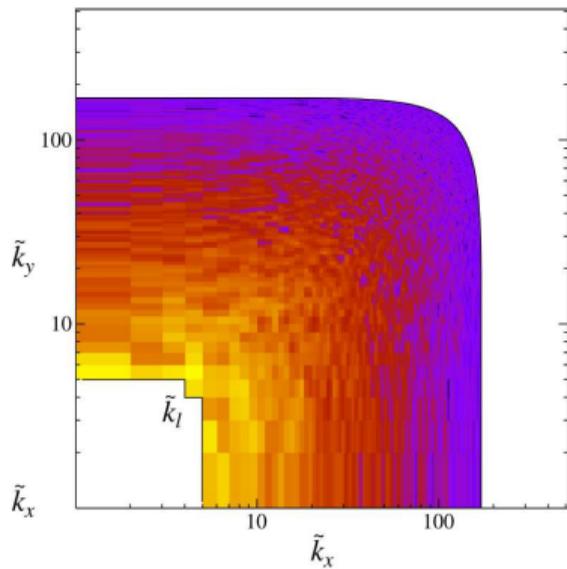


Fig. Power spectral density (Fourier space)
and corresponding rough surface (real space) for
 $k_l = 4$, $k_s = 171$

Effect of parameters: illustration

- Effect of the lower frequency cutoff k_l for $k_s/k_l = \text{const}$

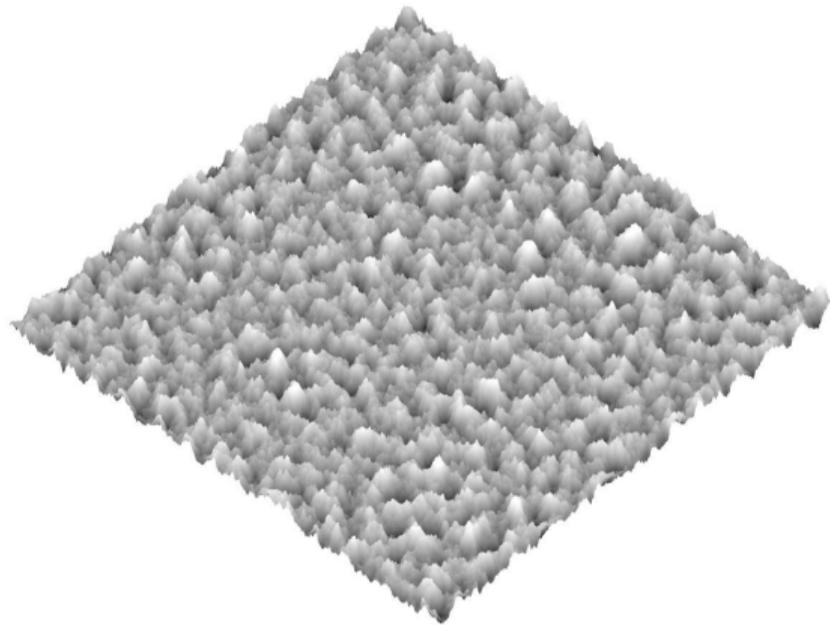
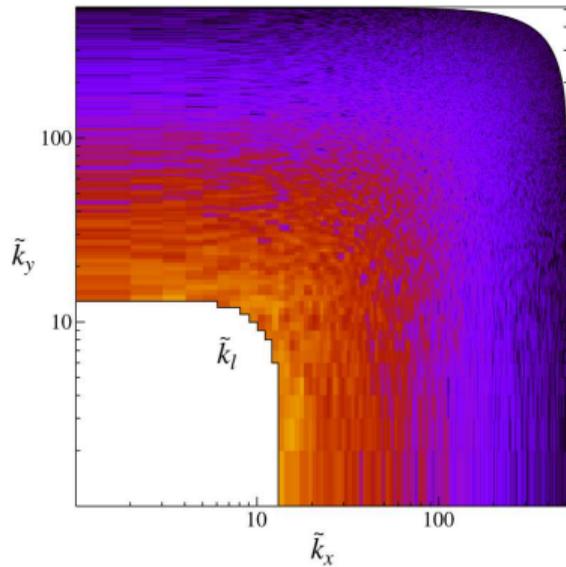


Fig. Power spectral density (Fourier space)
and corresponding rough surface (real space) for
 $k_l = 12, \quad k_s = 512$

Effect of parameters: illustration

- Effect of the ratio of the higher cutoff to the discretization k_s/N

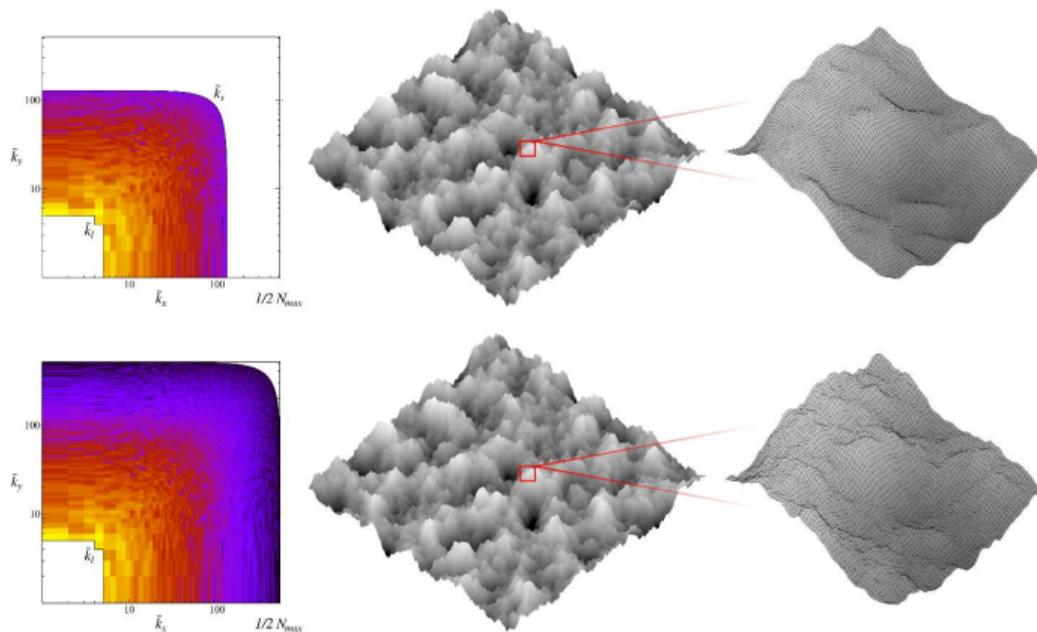


Fig. Power spectral densities (Fourier space)
and corresponding rough surfaces (real space) for
 $k_l = 12, k_s/N = 1/8$ VS $k_l = 12, k_s/N = 1/2$

Effect of parameters: illustration

- Effect of the ratio of the higher cutoff to the discretization k_s/N

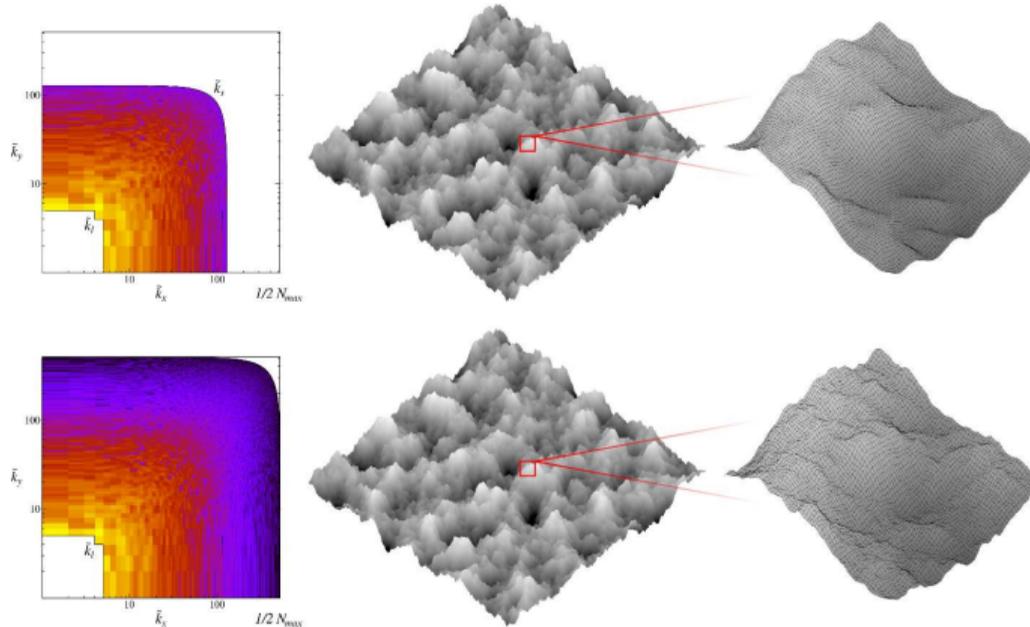


Fig. Power spectral densities (Fourier space) and corresponding rough surfaces (real space) for $k_l = 12$, $k_s/N = 1/8$ (**fine**) VS $k_l = 12$, $k_s/N = 1/2$ (**too coarse**) for mechanical simulations

Effect of parameters: illustration

- Data interpolation (Shanon, bi-cubic Bézier surfaces)

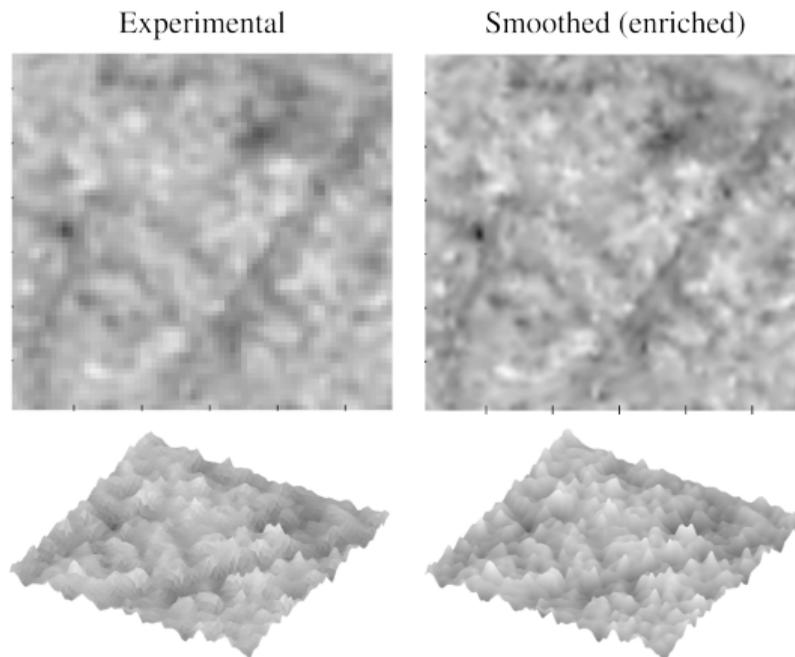


Fig. Bi-cubic Bézier interpolation of an experimental rough surface

[1] Hyun, Robbins, Tribol. Int. (2007)

[2] Yastrebov, Durand, Proudhon, Cailletaud, C.R. Mécan. (2011)

Asperity analysis

- Detect summits (z_{ij} higher than neighbor points) and evaluate second derivatives

$$\frac{\partial^2 z}{\partial x^2} = \frac{z_{i+1j} + z_{i-1j} - 2z_{ij}}{2\Delta x^2} \quad \frac{\partial^2 z}{\partial y^2} = \frac{z_{i+1j} + z_{i-1j} - 2z_{ij}}{2\Delta y^2} \quad \frac{\partial^2 z}{\partial x \partial y} = \frac{z_{i+1j+1} + z_{i+1j-1} - z_{i-1j+1} - z_{i-1j-1}}{4\Delta x \Delta y}$$

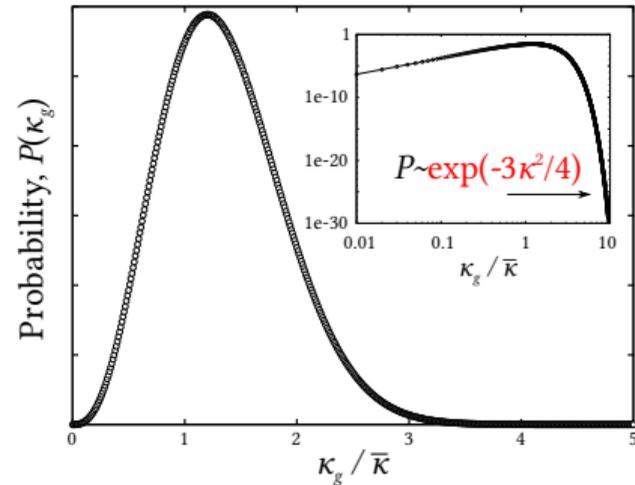
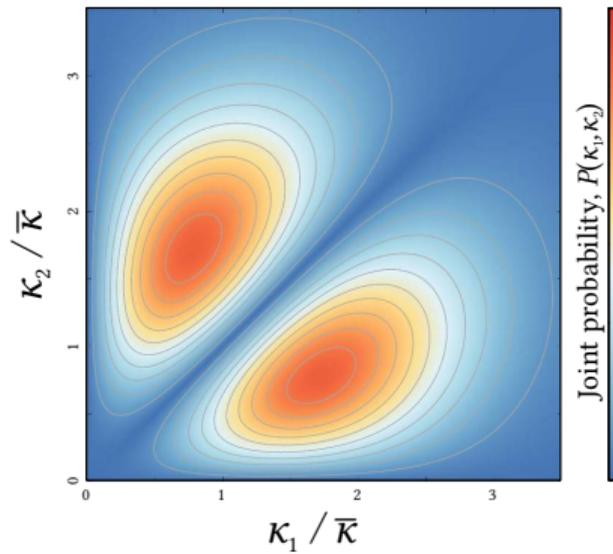
- Principal curvatures $\kappa_{1,2}$:

$$\kappa_{1,2} = \frac{1}{2} \left(\frac{\partial^2 z}{\partial x^2} + \frac{\partial^2 z}{\partial y^2} \right) \pm \sqrt{\left(\frac{\partial^2 z}{\partial x \partial y} \right)^2 + \frac{1}{4} \left(\frac{\partial^2 z}{\partial x^2} - \frac{\partial^2 z}{\partial y^2} \right)^2}$$

- Saddle point $\kappa_1 \kappa_2 < 0$, extrema $\kappa_1 \kappa_2 > 0$
- Mean geom. curvature which can be safely used in Hertz theory:

$$\bar{\kappa} = \sqrt{\kappa_1 \kappa_2}$$

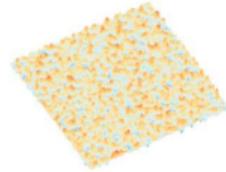
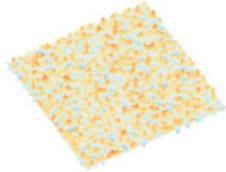
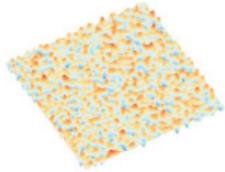
Asperity analysis



$$P \sim \kappa^2 \exp(-3\kappa^2/4) \operatorname{erf}(3\kappa/2)$$

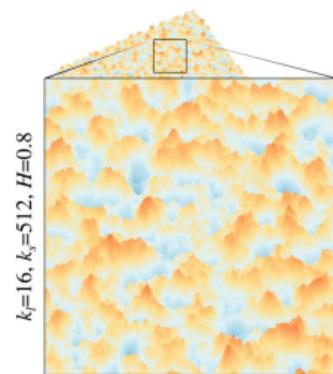
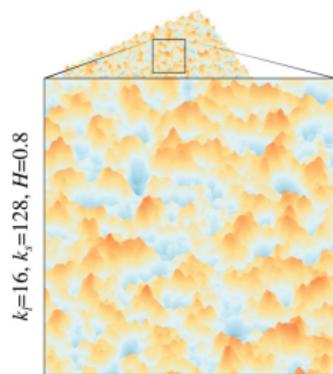
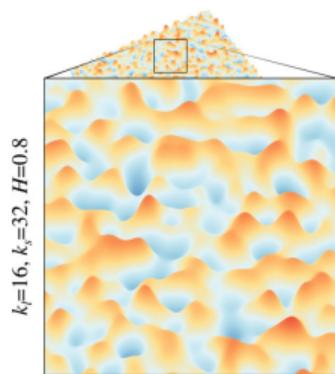
Statistics of asperity curvature

Asperity analysis



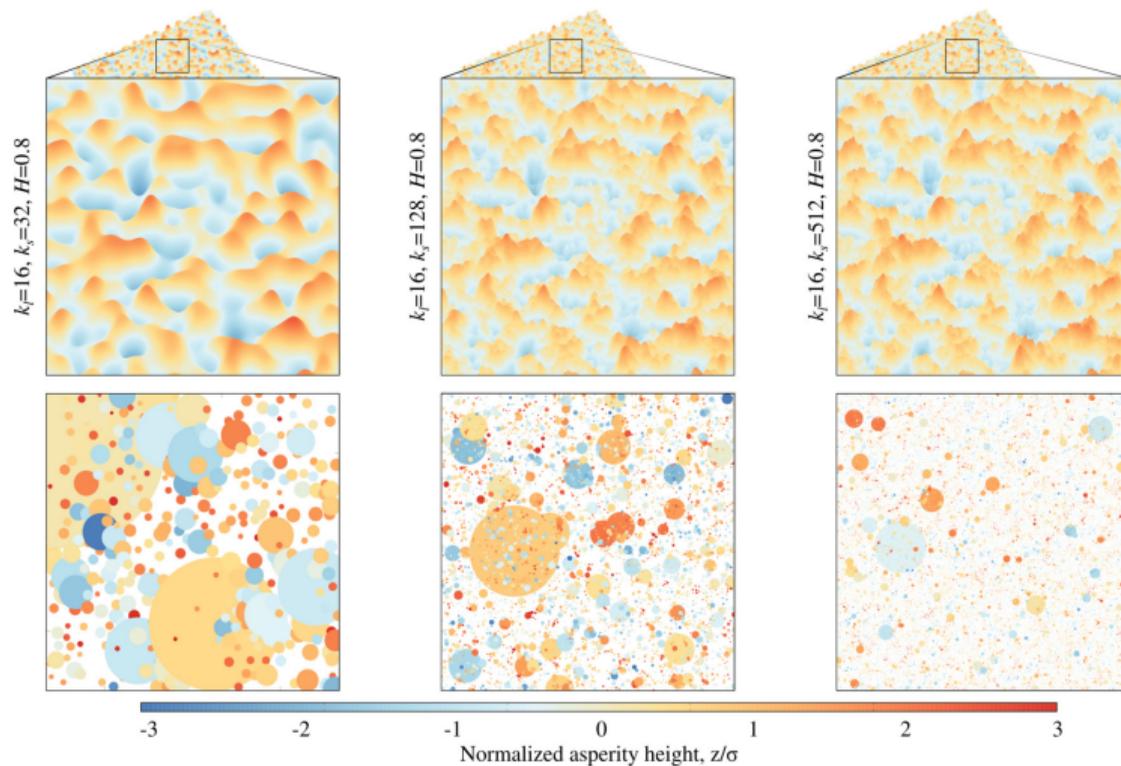
Rough surfaces and associated asperities

Asperity analysis



Rough surfaces and associated asperities

Asperity analysis



Rough surfaces and associated asperities

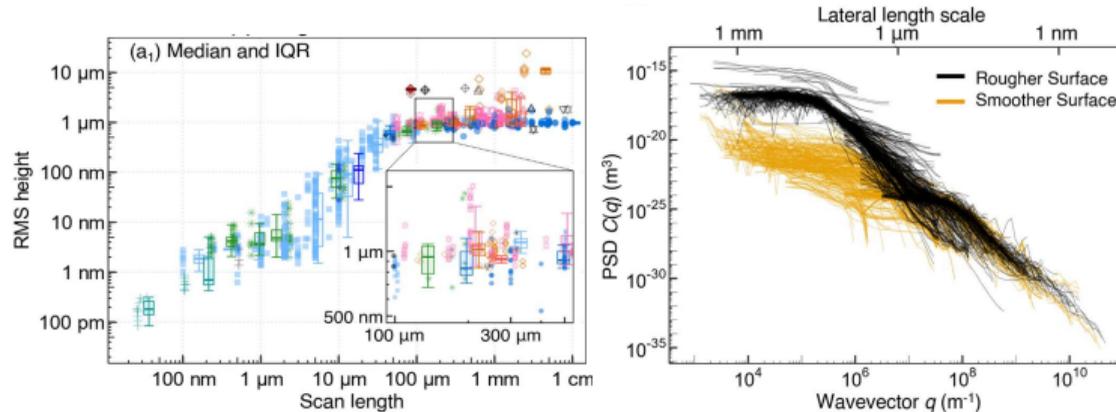
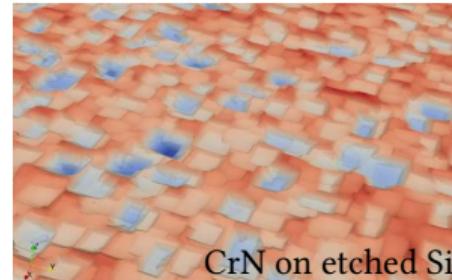
- Surface roughness metrology:
stylus, confocal, WLI, AFM, STM
- Roughness characteristics:
PDF, PSD, Hurst exp., spectral moments, Nayak parameter...
- How to model roughness
- Fractal aspect & Mandelbrot set
- Asperity characteristics

The Surface-Topography Challenge

A. Pradhan, M.H. Müser, L. Pastewka, T. Jacobs *et al.*, Tribology Letters 73, 2025

Data

- 20 countries
- 64 research groups
- 153 scientists and engineers
- 2088 measurements (FAIR data)

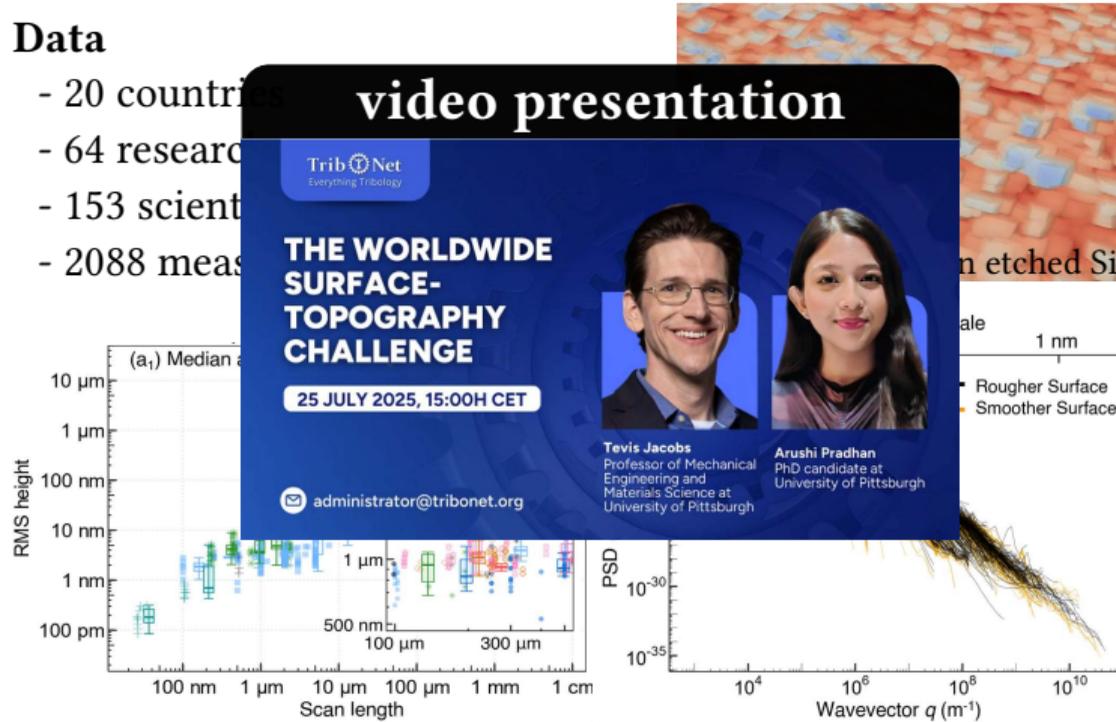


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Thank you for your attention!
